



Introduction to Quantitative XRF analysis

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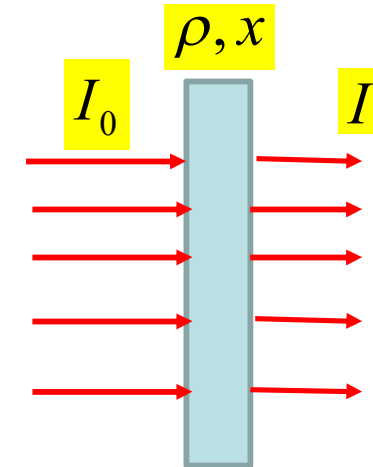
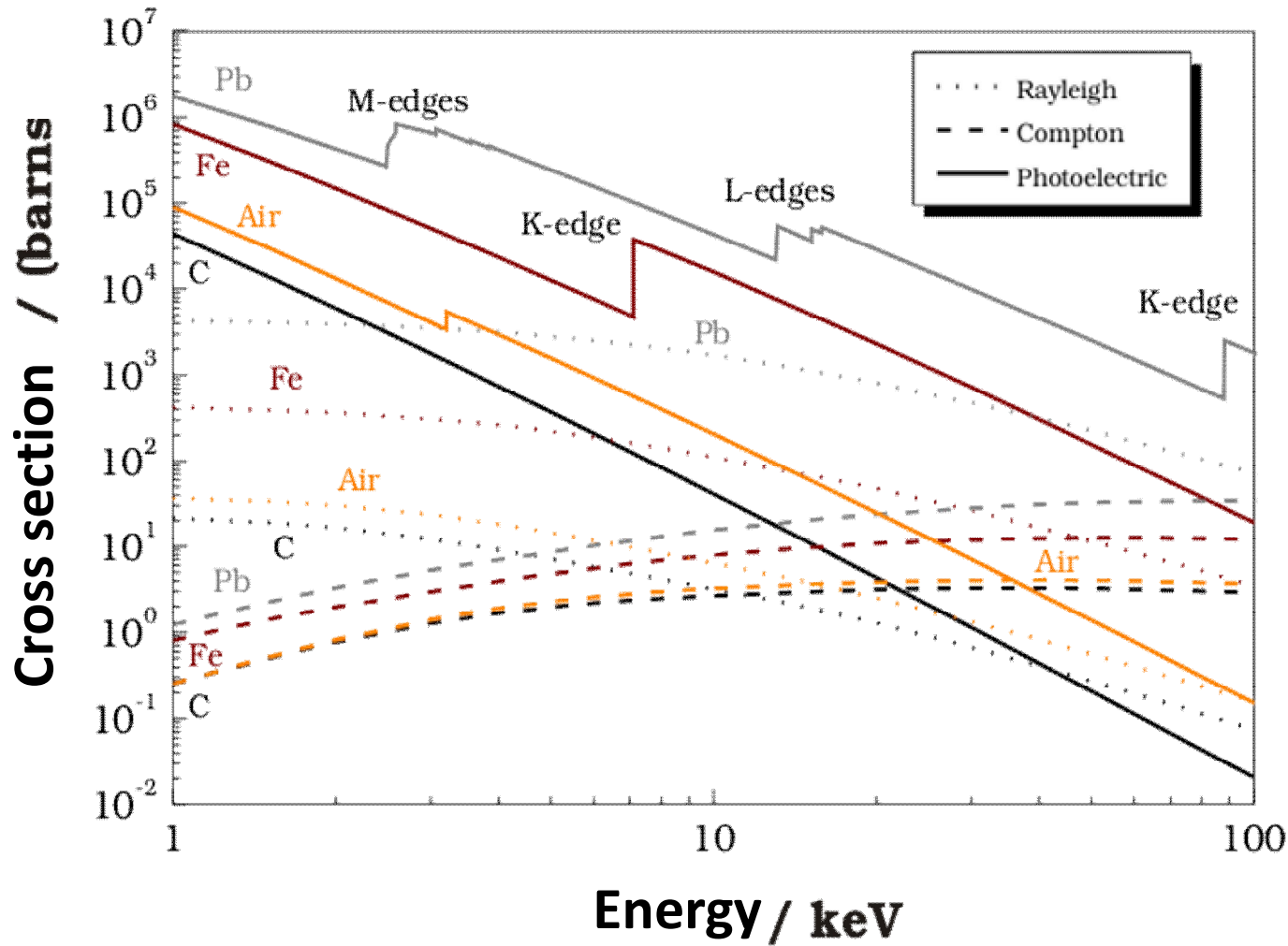


Karydas, ICTP-IAEA School, Trieste, 18th November 2014

Outline

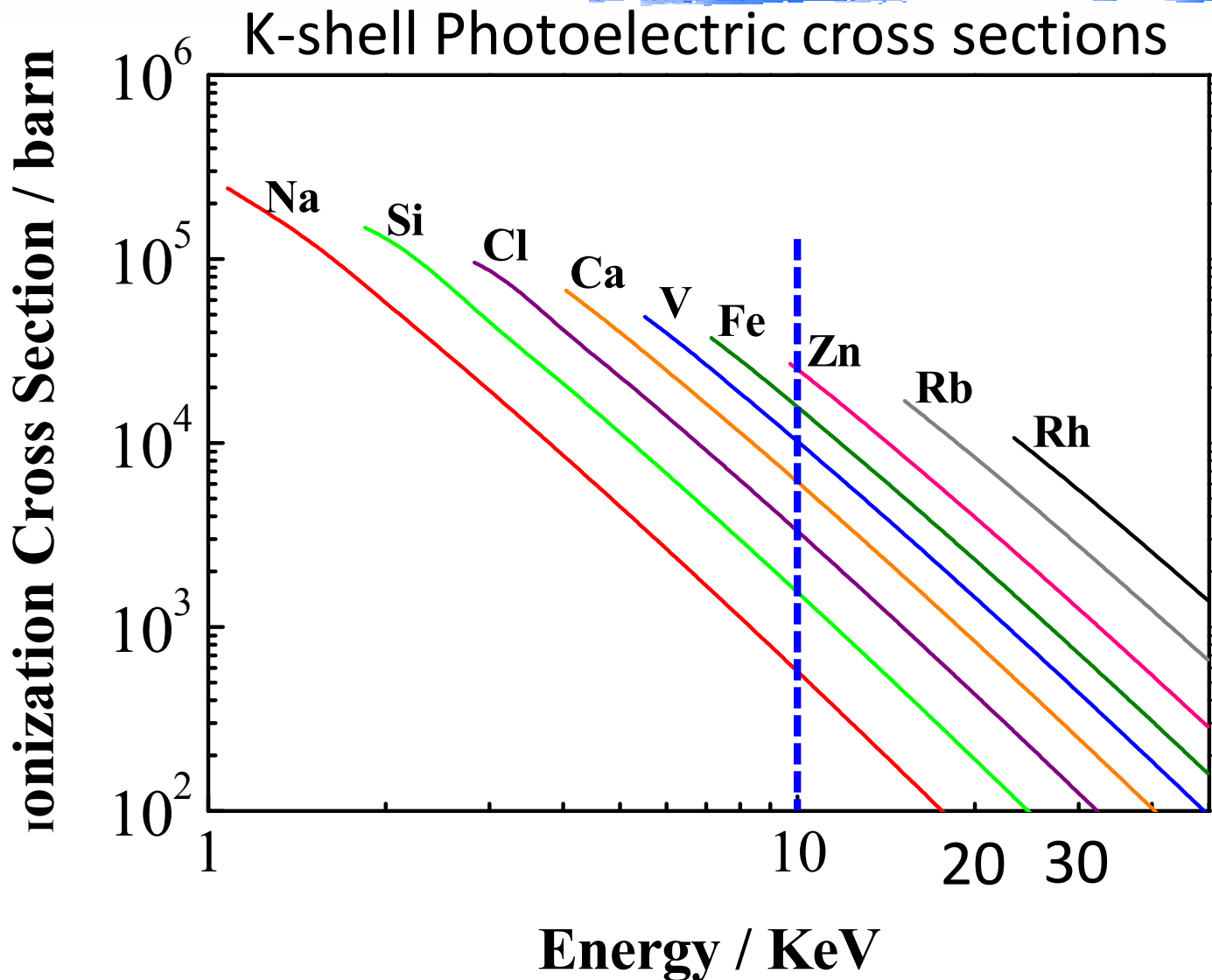
- Basic mechanisms for ionization/fluorescence process
- Primary XRF Intensity
- Indirect enhancement processes of XRF intensity
- XRF analysis in the real world:
 - Non-parallel exciting beams
 - Influence of surface topography
 - Geometrical considerations
 - Particle size effects

Interaction of X-rays with atoms



$$I = I_0 \cdot e^{-(\tau + \sigma_R + \sigma_C) \cdot \rho \cdot x}$$

Photoelectric cross sections



10⁴-10⁵ b

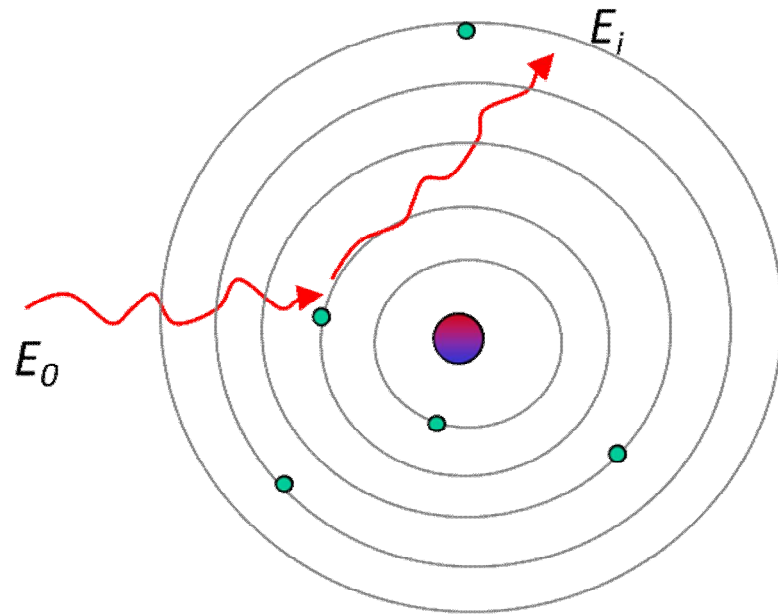
Photon ICS from
 "Elam database"
 Elam W.T. et al.,
Radiat. Phys. Chem, 63,
 (2002), 121

Photoelectric
 cross section:

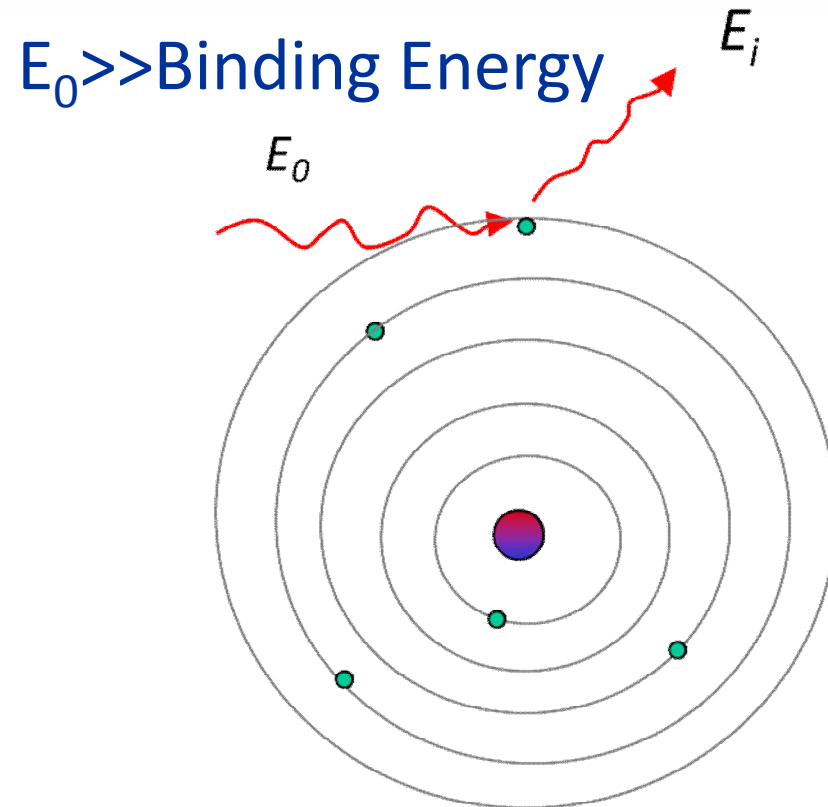
$$\tau \sim E^{-3.5}$$

$$\tau \sim Z^3 \text{ to } 4$$

X-ray Scattering Interactions with atoms



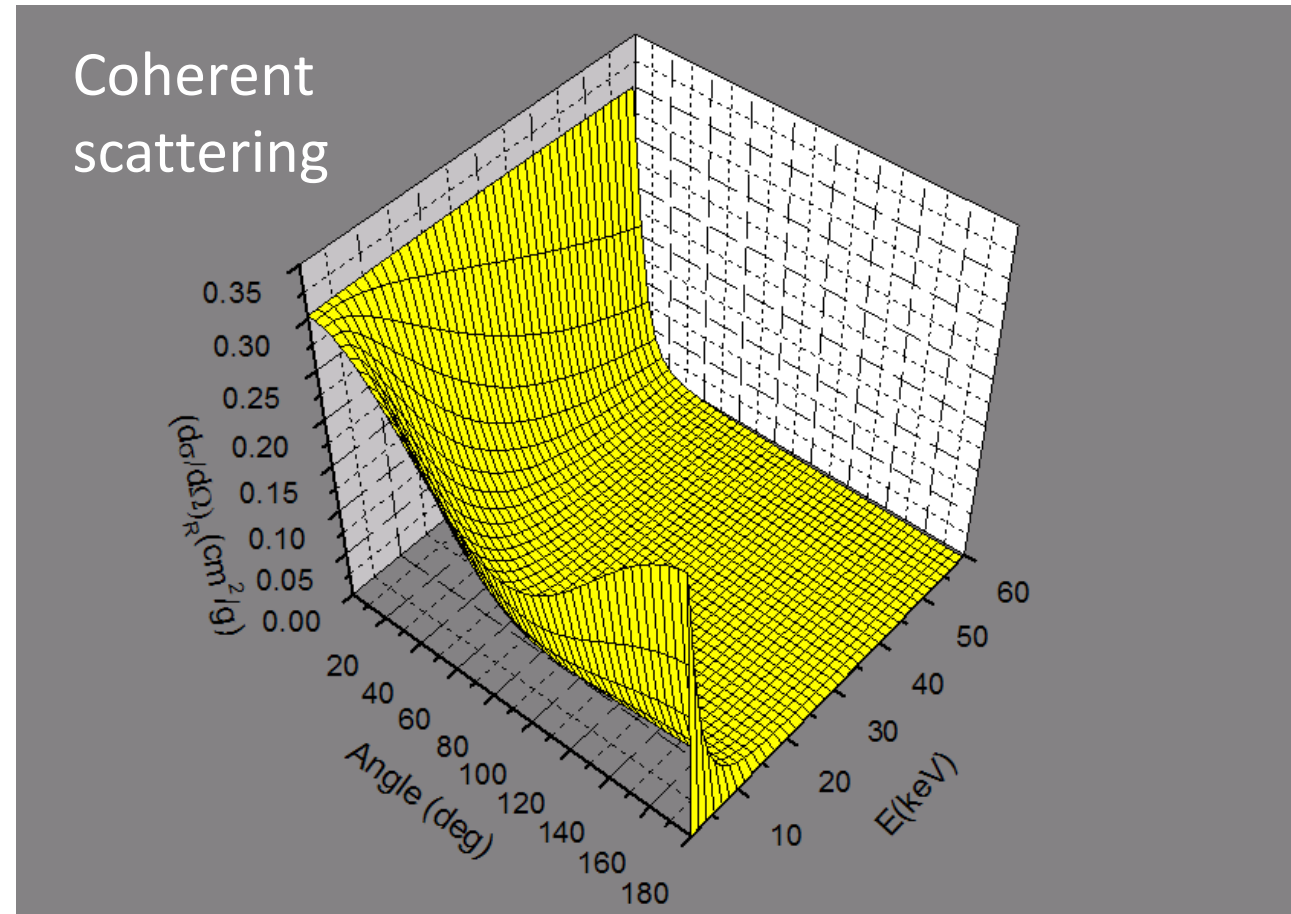
$E_i = E_0$: Coherent (Rayleigh),
mostly with inner atomic
electrons



**$E_i < E_0$: Incoherent
(Compton),** mostly with
outer, less bound
electrons

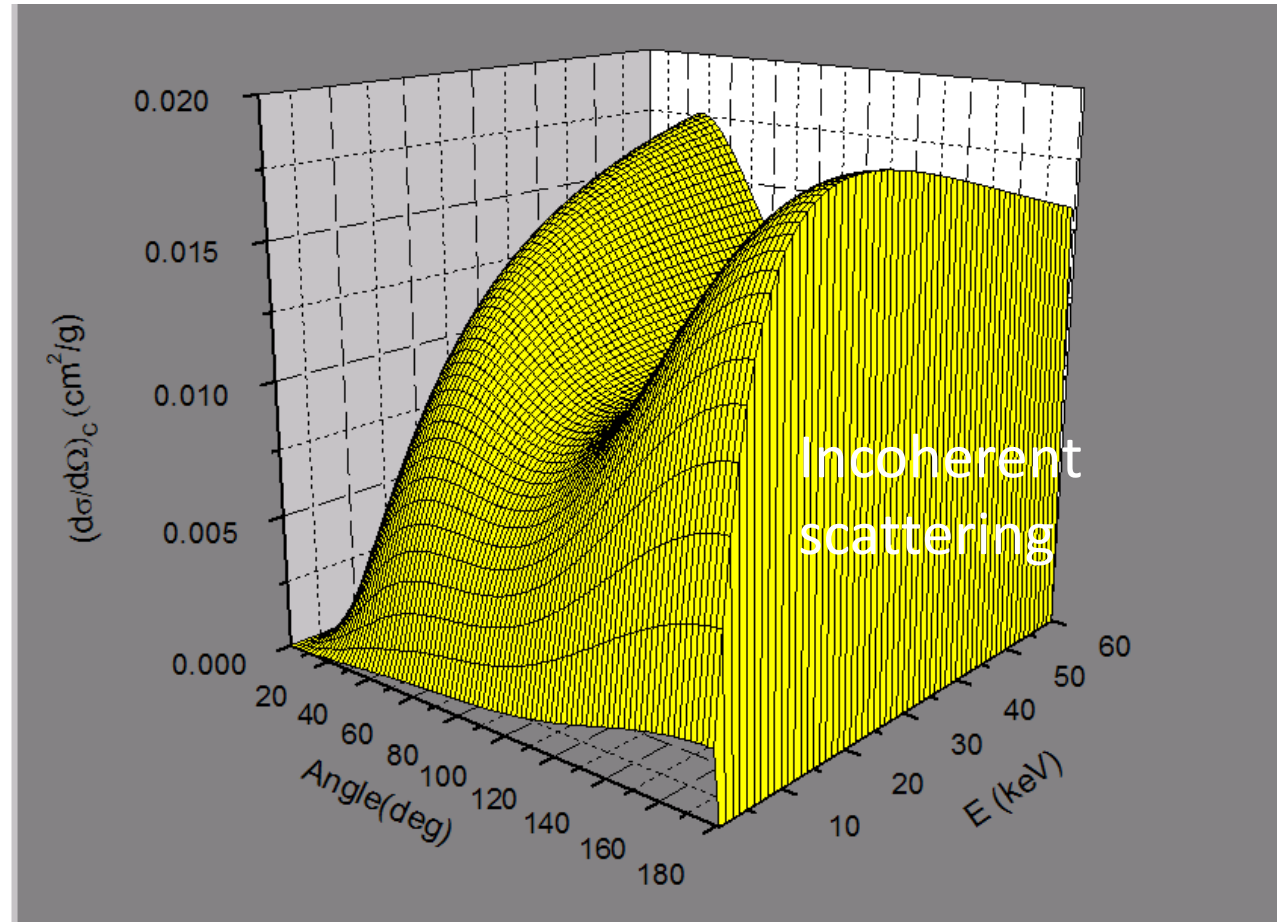
Scattering probabilities: Unpolarized excitation

Z	WF (%)
Al	8.4
Si	26.7
Ca	9.3
Fe	9.8



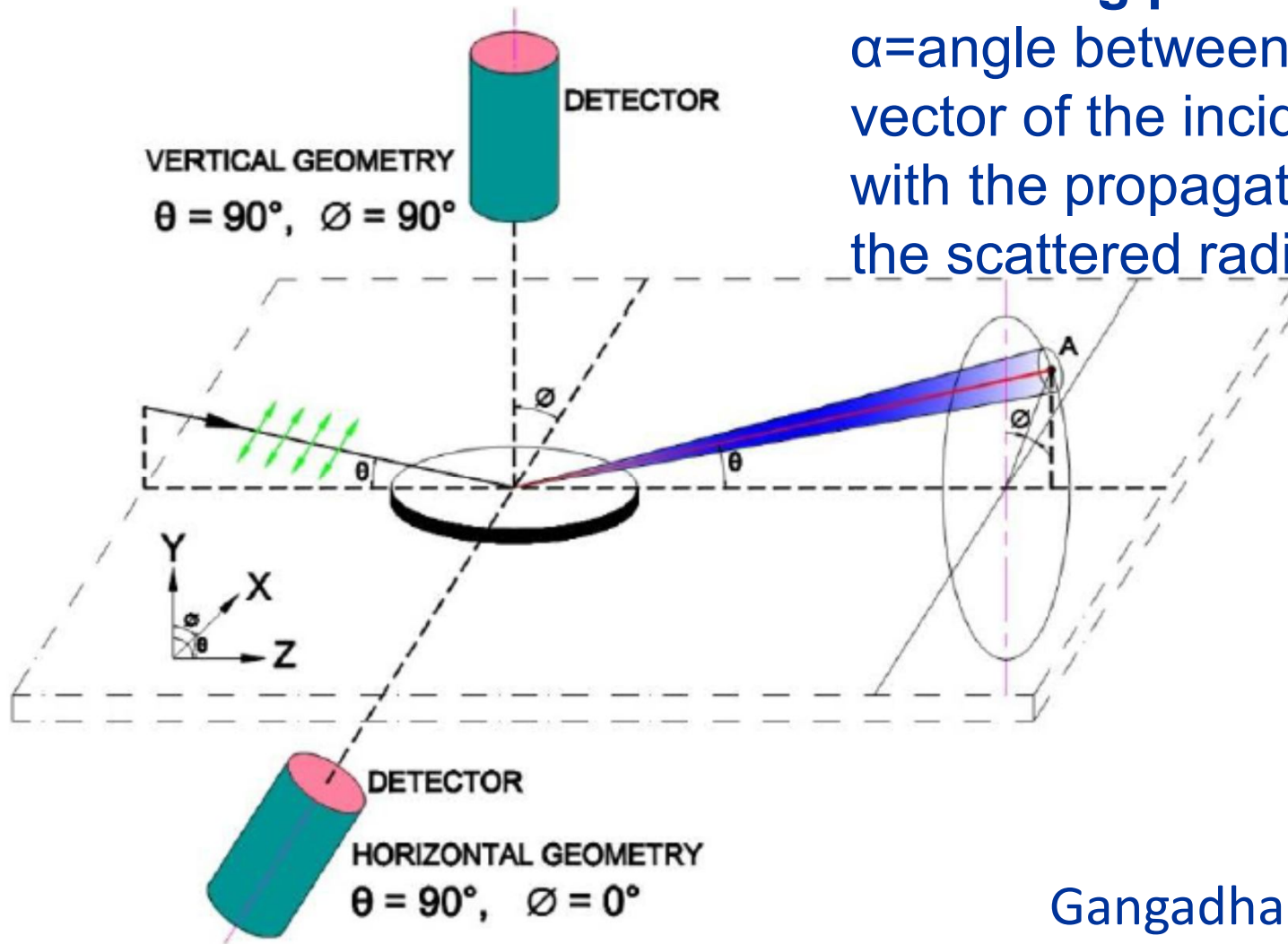
Scattering probabilities: Unpolarized excitation

Z	WF (%)
Al	8.4
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Ca	9.3
Fe	9.8



Scattering probabilities: Polarized radiation

Scattering probability $\sim \sin^2\alpha$
 α =angle between electric field vector of the incident radiation with the propagation direction of the scattered radiation



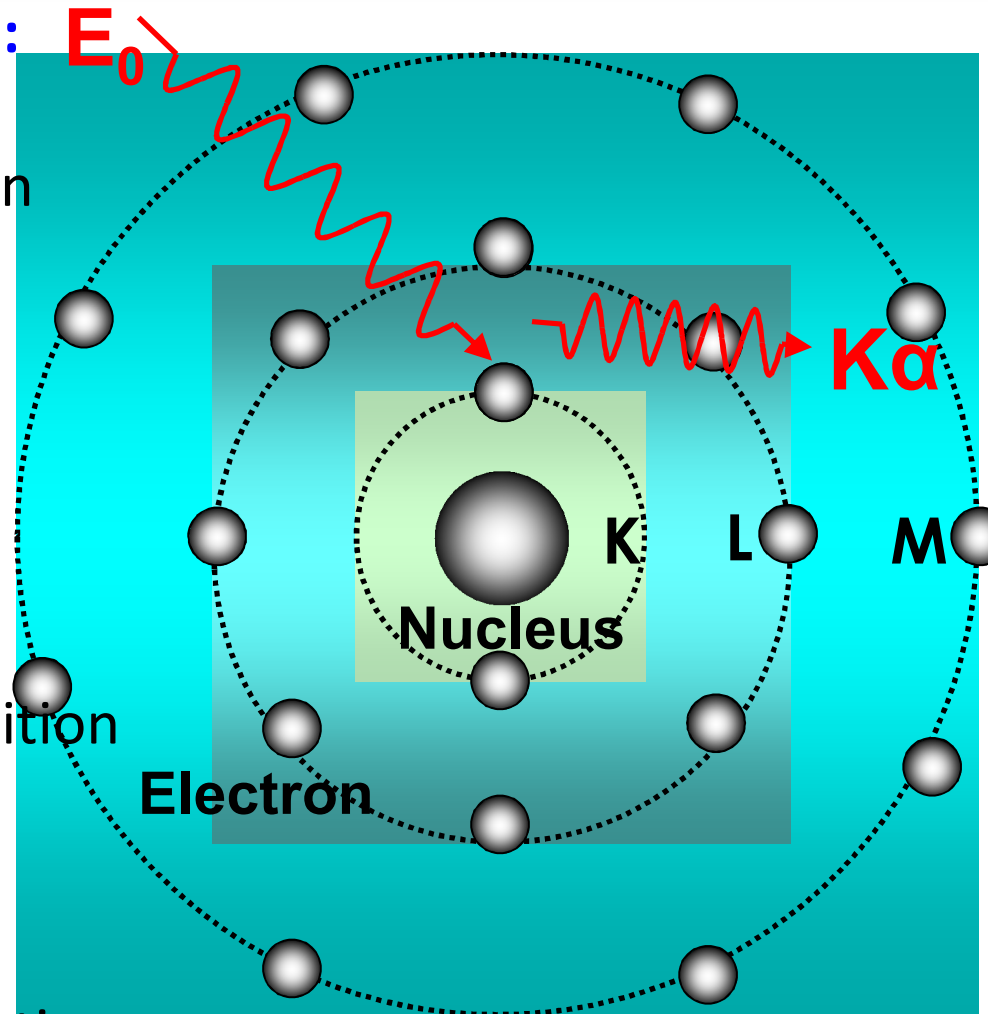
Gangadhar et al. JAAS, 2014

Working principle: X-Ray Fluorescence Analysis

Working principle:

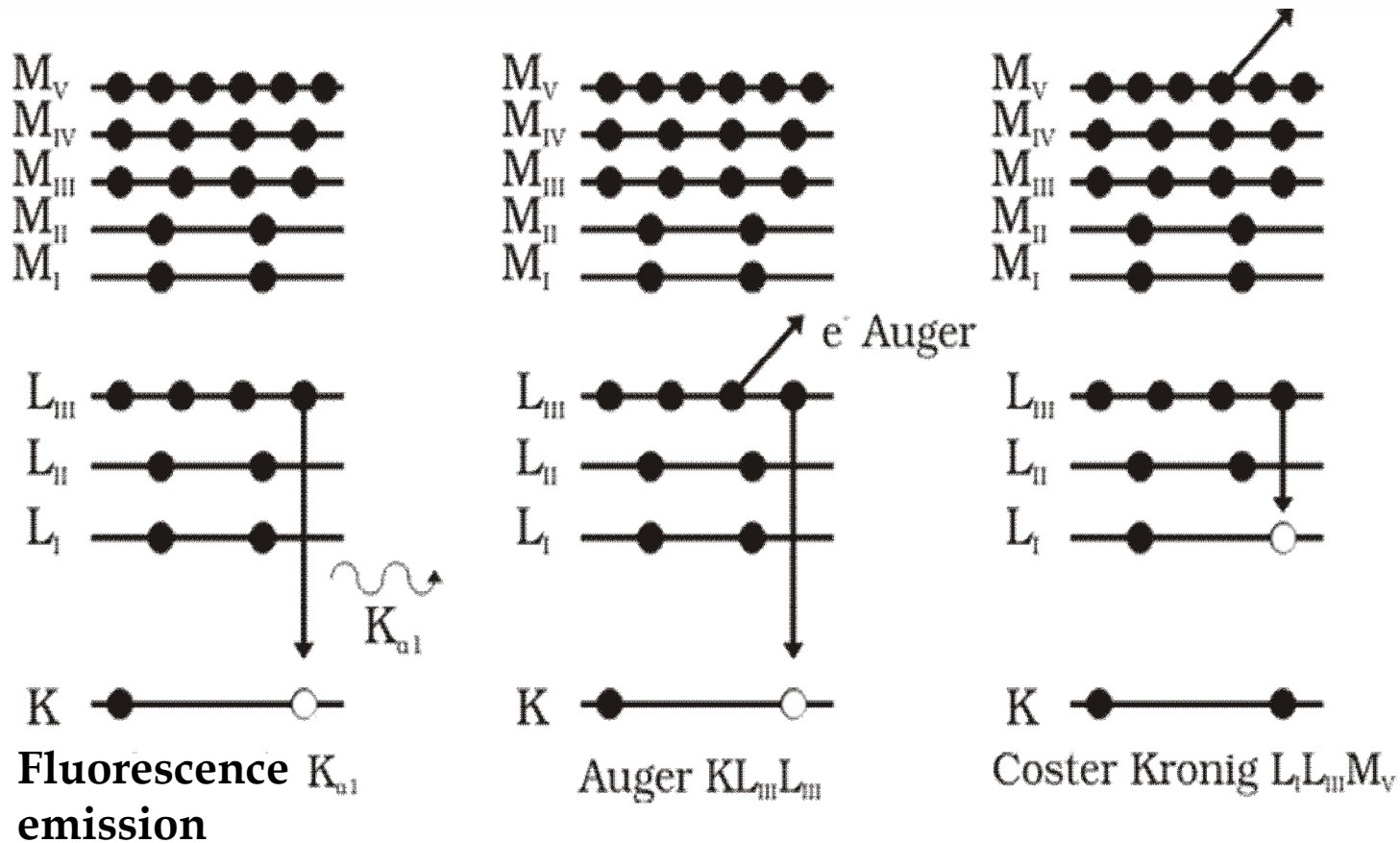
1) Photo-ionization of atomic bound electrons (K, L, M) /Photoelectric absorption

2) Electronic transition and emission of element 'characteristic' fluorescence radiation



Incident photon Energy E_0 should be adequate to ionize the atomic bound electrons \geq Atomic shell Binding energy

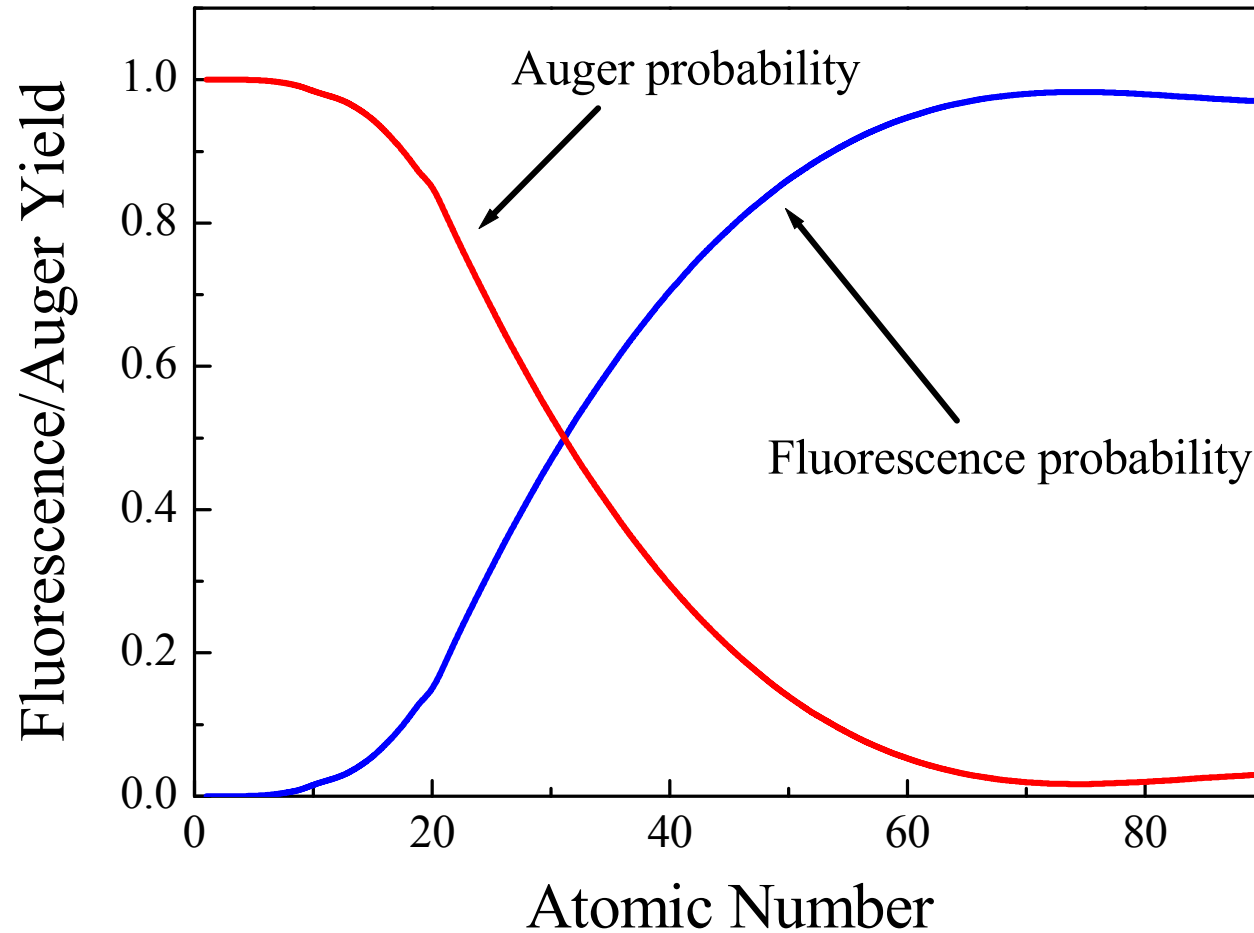
De-excitation of atoms: Competitive processes



ω_K : K-shell fluorescence yield

f_{Lij} : Coster-Cronig (intra-shell) transition probabilities from the i to the j L subshell

De-excitation: Fluorescence/Auger yield



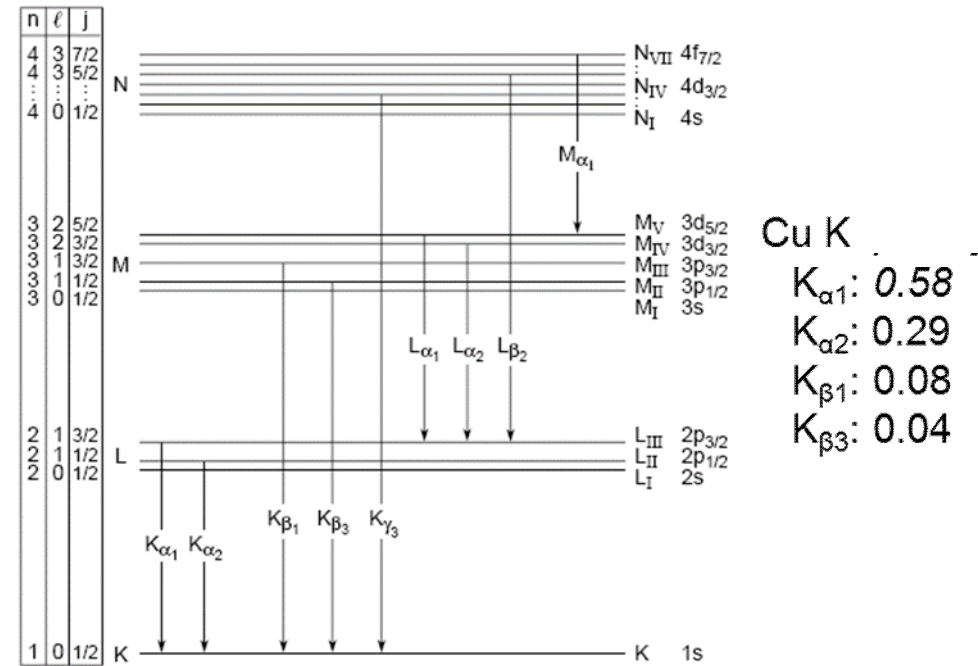
Emission of element 'characteristic' x-rays

K - alpha lines: L shell e- transition to fill vacancy in K shell. Most frequent transition, hence most intense peak

K - beta lines: M shell e- transitions to fill vacancy in K shell.

L - alpha lines: M shell e- transition to fill vacancy in L shell.

L - beta lines: N shell e- transition to fill vacancy in L shell.



L_3 to K shell → $E_{K\alpha 1} = U_K - U_{L3}$

Each element has a unique set of emission energies

XRF cross sections: K- Emission

XRF K-shell fluorescence cross section, $\sigma_{KX}(E_o)$

$$\sigma_{KX}(E_o) = \tau_K(E_o) \cdot \omega_K \cdot F_{KX}$$

$\tau_K(E_o)$: K-shell photoelectric cross section (*cm²/g or barns/atom*)

ω_K : K-shell fluorescence yield

f_{KX} : Transition probability for K α emission

XRF cross sections: L- Emission

Example: Incident energy $E_o > U_{L1}$

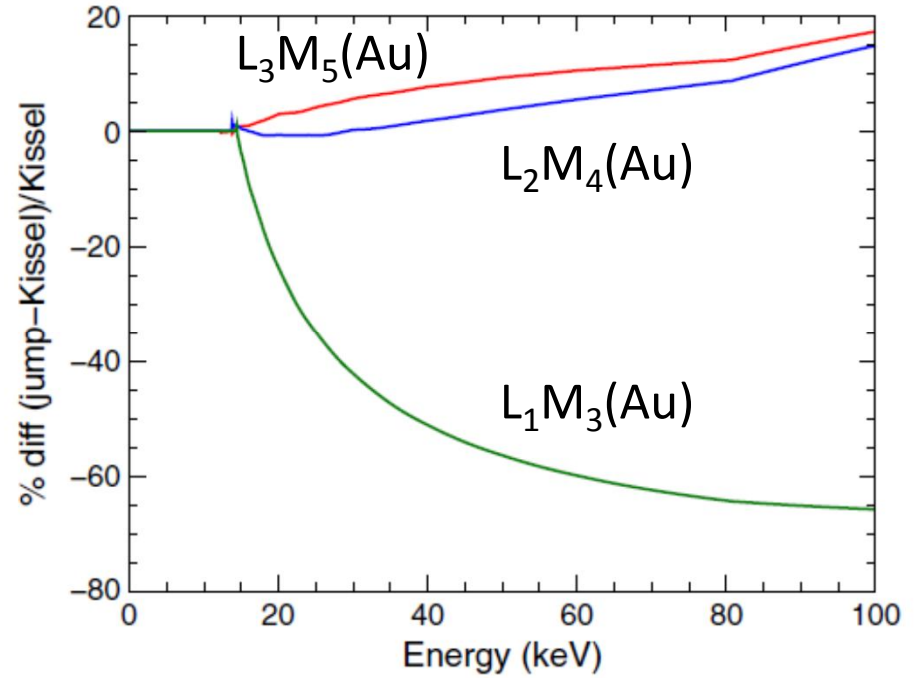
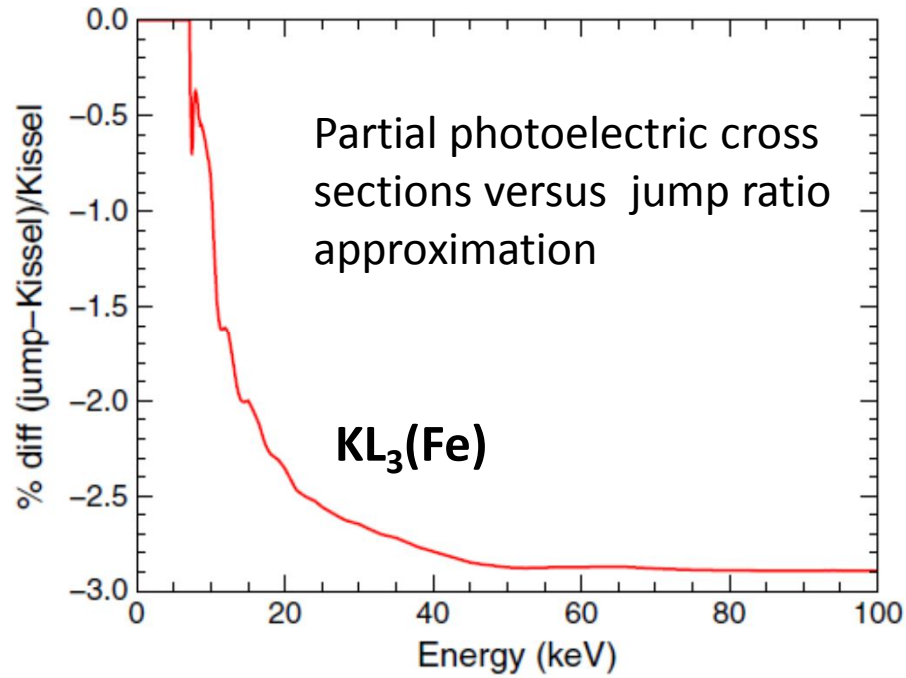
$$\sigma_{L1X}(E_o) = \tau_{L1}(E_o) \cdot \omega_{L1}(Z_i) \cdot f_{L1X}(Z_i)$$

$$\sigma_{L2X}(E_o) = (\tau_{L2} + \tau_{L1} \cdot f_{L12}) \cdot \omega_{L1}(Z_i) \cdot f_{L2X}(Z_i)$$

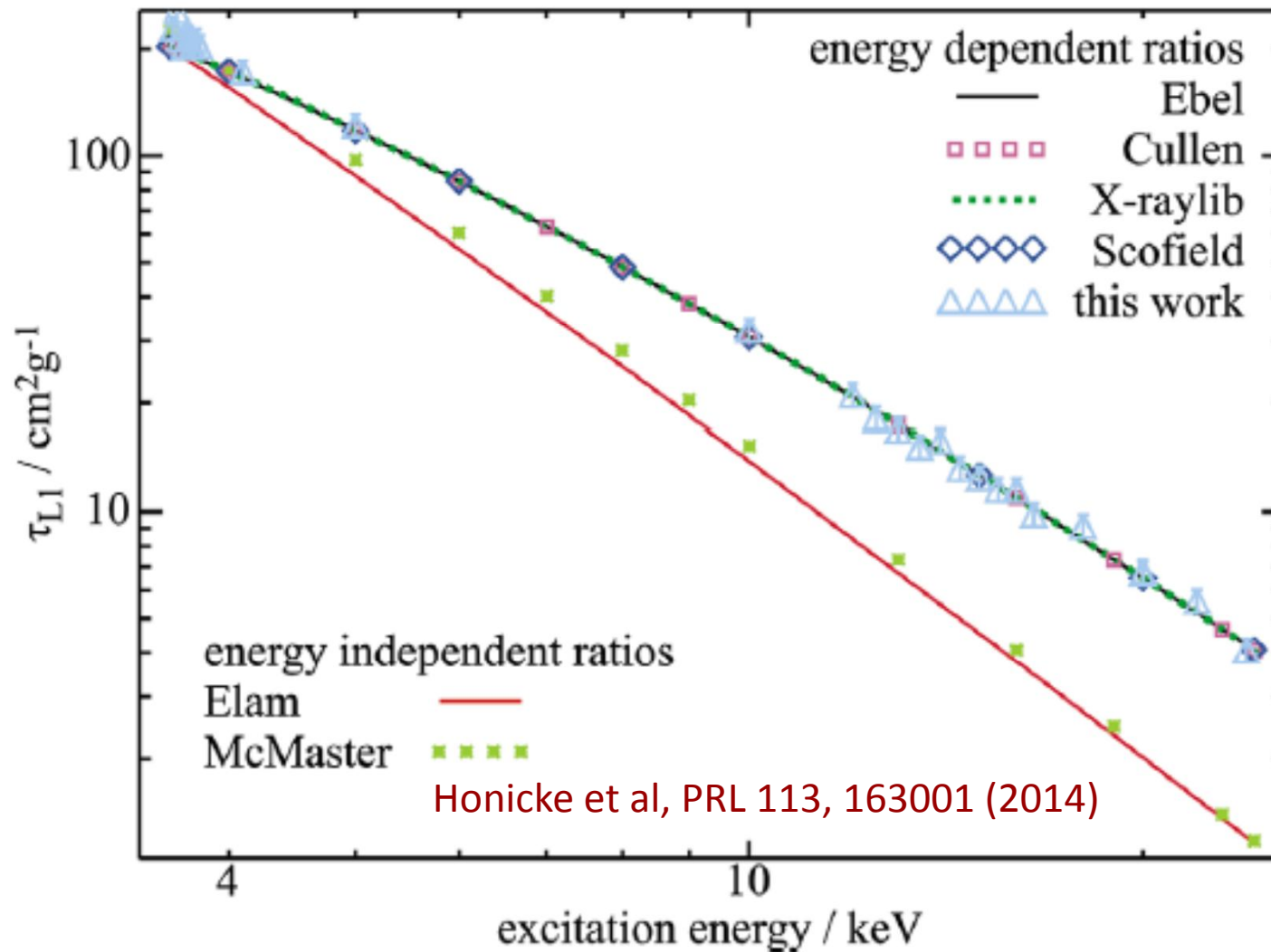
$$\sigma_{L3X}(E_o) = (\tau_{L3} + \tau_{L2} \cdot f_{L23} \cdot f_{L12} + \tau_{L1} \cdot f_{L13}) \cdot \omega_{L3}(Z_i) \cdot f_{L3X}(Z_i)$$

f_{Lij} : Coster-Cronig (intra-shell) transition probabilities from the i to the j L subshell

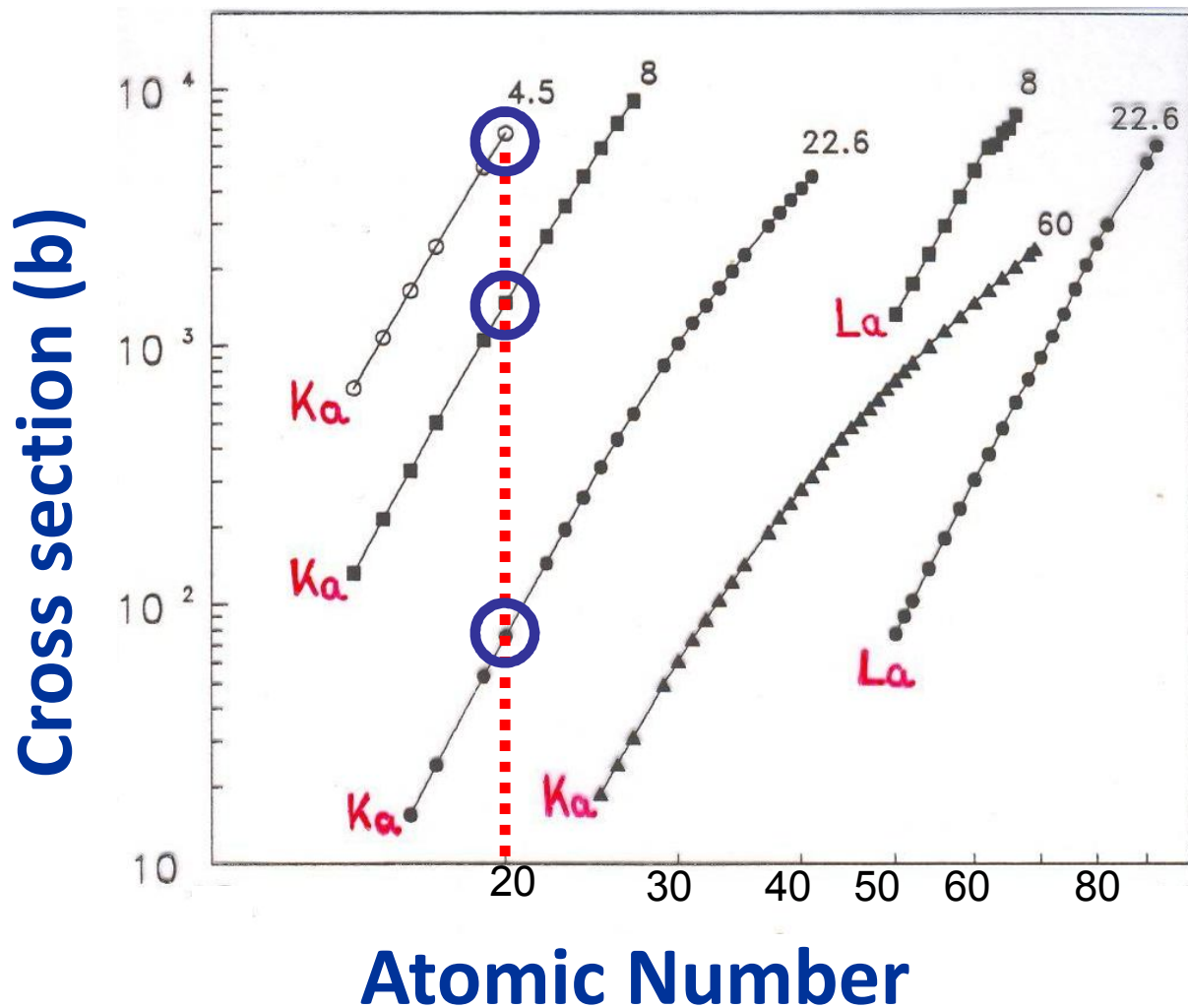
XRF cross sections: L- Emission



XRF cross sections: L- Emission



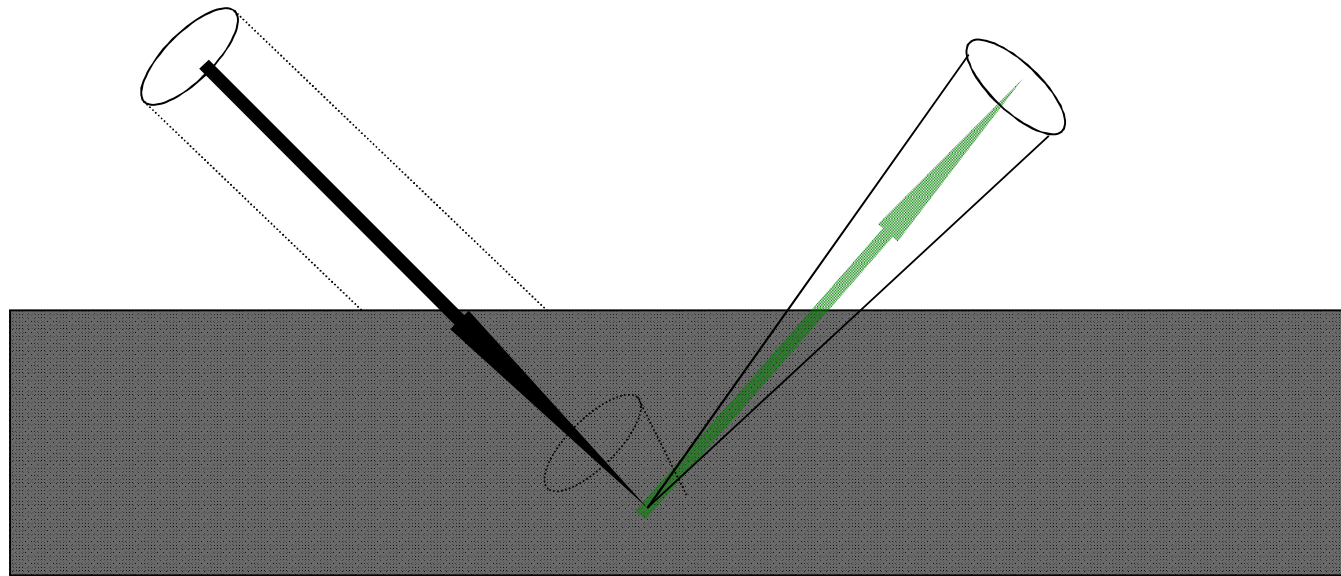
Fluorescence $K\alpha$, $L\alpha$ cross sections



Optimization of the exciting beam energy for maximizing the characteristic X-ray intensity

Primary Fluorescence intensity: Assumptions

- Parallel incident beam
 - Infinite surface for sample
 - Beam cross section infinite
 - Homogenous sample
 - Flat surface of the sample
- D.K.G. de Boer, XRS, 19(1990) 145
 - M. Mantler, in Handbook of Practical XRFA, Edited by B. Beckhoff et al.



Primary Fluorescence intensity: Assumptions

Spectrochimica Acta, 1955, Vol 7, pp 283 to 306. Pergamon Press Ltd., London

The theoretical derivation of fluorescent X-ray intensities from mixtures*

JACOB SHERMAN

Philadelphia Naval Shipyard, Philadelphia 12, Pennsylvania

(Received 4 August 1955)

JAPANESE JOURNAL OF APPLIED PHYSICS

VOL. 5, NO. 10, OCTOBER, 1956

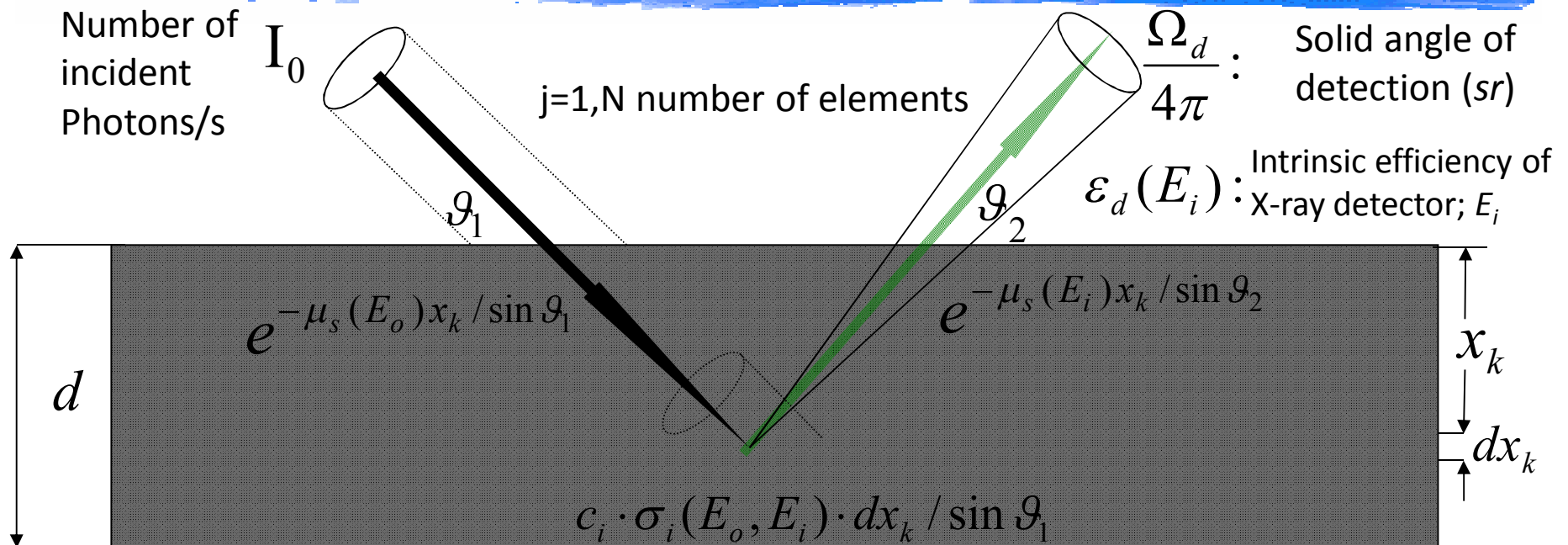
Theoretical Calculation of Fluorescent X-Ray Intensities in Fluorescent X-Ray Spectrochemical Analysis.

Toshio SHIRAIWA and Nobukatsu FUJINO

*Physics Section, Central Research Laboratories,
Sumitomo Metal Industries, Amagasaki, Hyogo.*

(Received April 15, 1966)

Primary Fluorescence intensity



(Concentration of i element) X (Fluorescence cross section; cm^2/g) X (areal density; g/cm^2)

$$\mu_s(E_o) : \text{Sample mass attenuation coefficient for energy } E_o \equiv \sum_{j=1, N} c_j \mu_j(E_o)$$

$$dI_i(E_i) = I_o \cdot e^{-\mu_s(E_o) \cdot x_k / \sin \vartheta_1} \cdot c_i \cdot \sigma_i(E_o, E_i) \cdot \frac{dx_k}{\sin \vartheta_1} \cdot e^{-\mu_s(E_i) \cdot x_k / \sin \vartheta_2} \cdot \frac{\Omega_d}{4 \cdot \pi} \cdot \epsilon_d(E_i)$$

$$\mu_T(E_o, E_i) \equiv \mu_s(E_o) / \sin \vartheta_1 + \mu_s(E_i) / \sin \vartheta_2$$

Primary Fluorescence intensity: Calibration

$$I_i(E_i) = \text{[redacted]} c_i \cdot \frac{1 - e^{-\mu_T(E_o, E_i) \cdot d}}{\mu_T(E_o, E_i)} \cdot \text{[redacted]}$$

Sensitivity $S_i(E_o, E_i)$

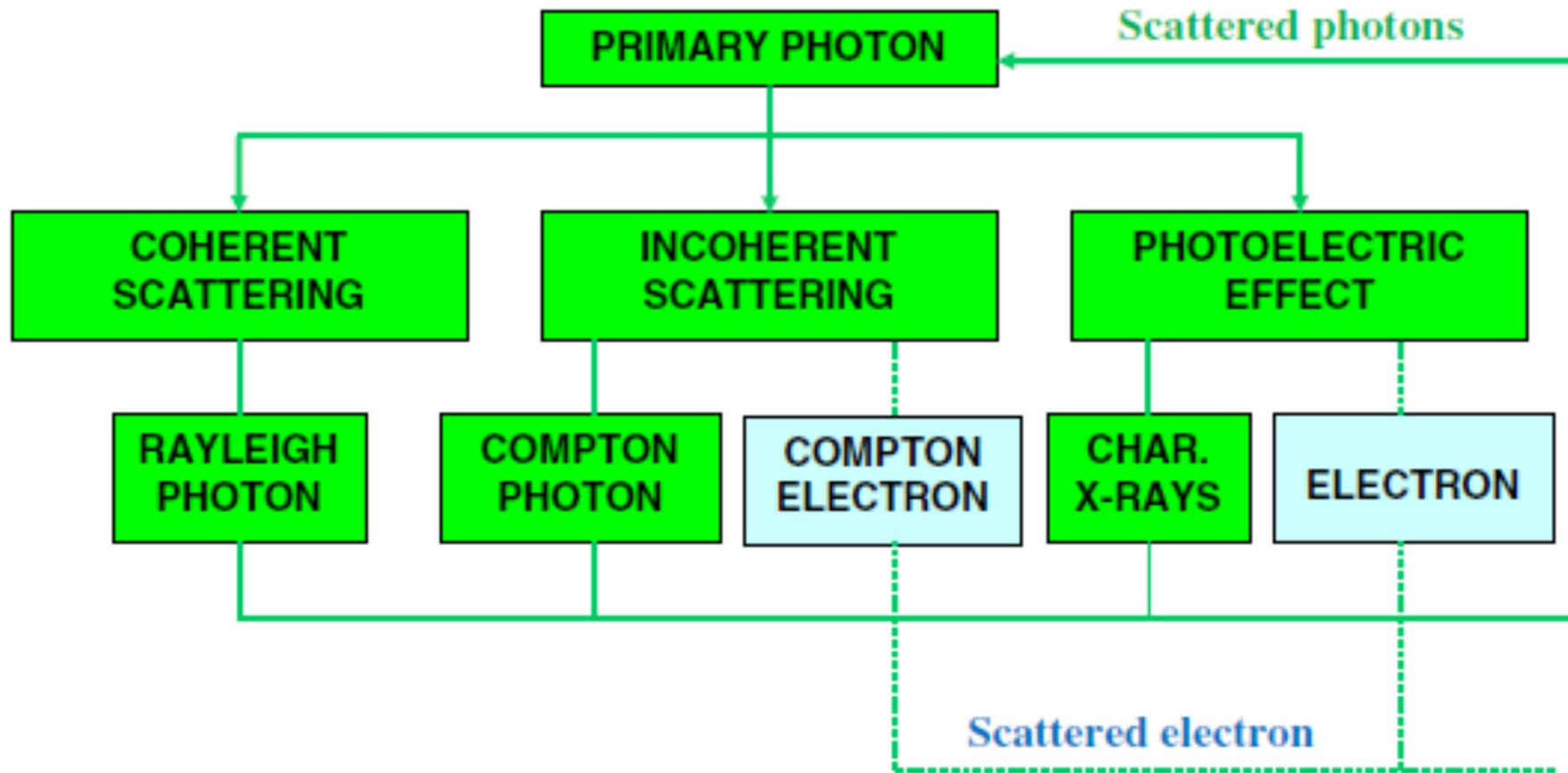
$$\mu_T(E_o, E_i) \cdot d \gg 1 \quad I_i(E_i) = S_i(E_o, E_i) \cdot c_i \cdot \frac{1}{\mu_T(E_o, E_i)} \quad \text{Thick target approximation}$$

$$\mu_T(E_o, E_i) \cdot d \ll 1 \quad I_i(E_i) = S_i(E_o, E_i) \cdot c_i \cdot d \quad \text{Thin target}$$

Different approaches are followed depending on how well the set-up geometry and incident beam intensity are characterized:

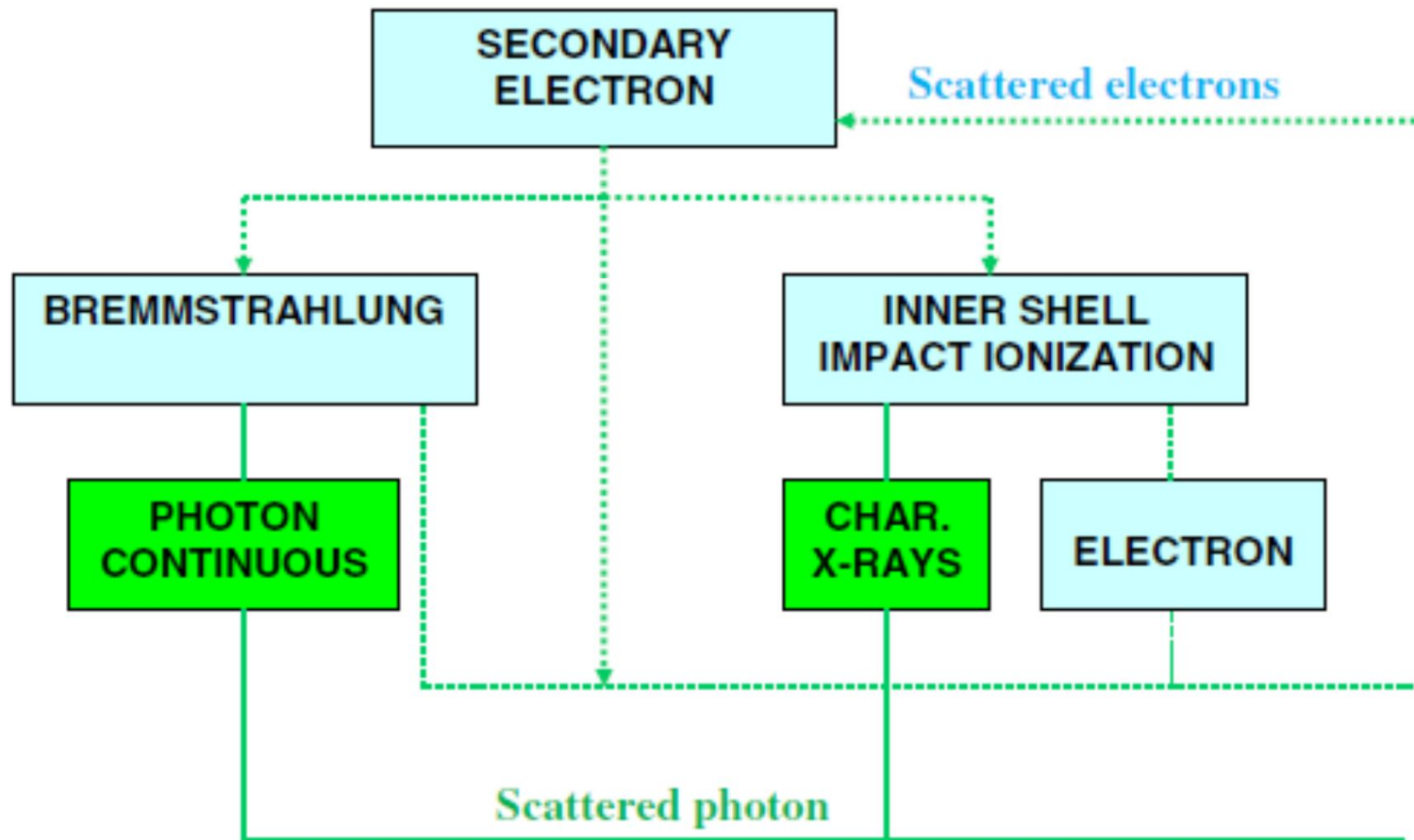
- **Sensitivity calibration:** certified pure element/compound targets
- **Solid angle calibration:** Normalized beam intensity, detector efficiency known, well certified pure element/compound targets
- **Standard-less XRFA:** Calibrated apertures, distances, detector response function versus energy, incident beam intensity

Indirect Enhancement Processes in Fluorescence Emission



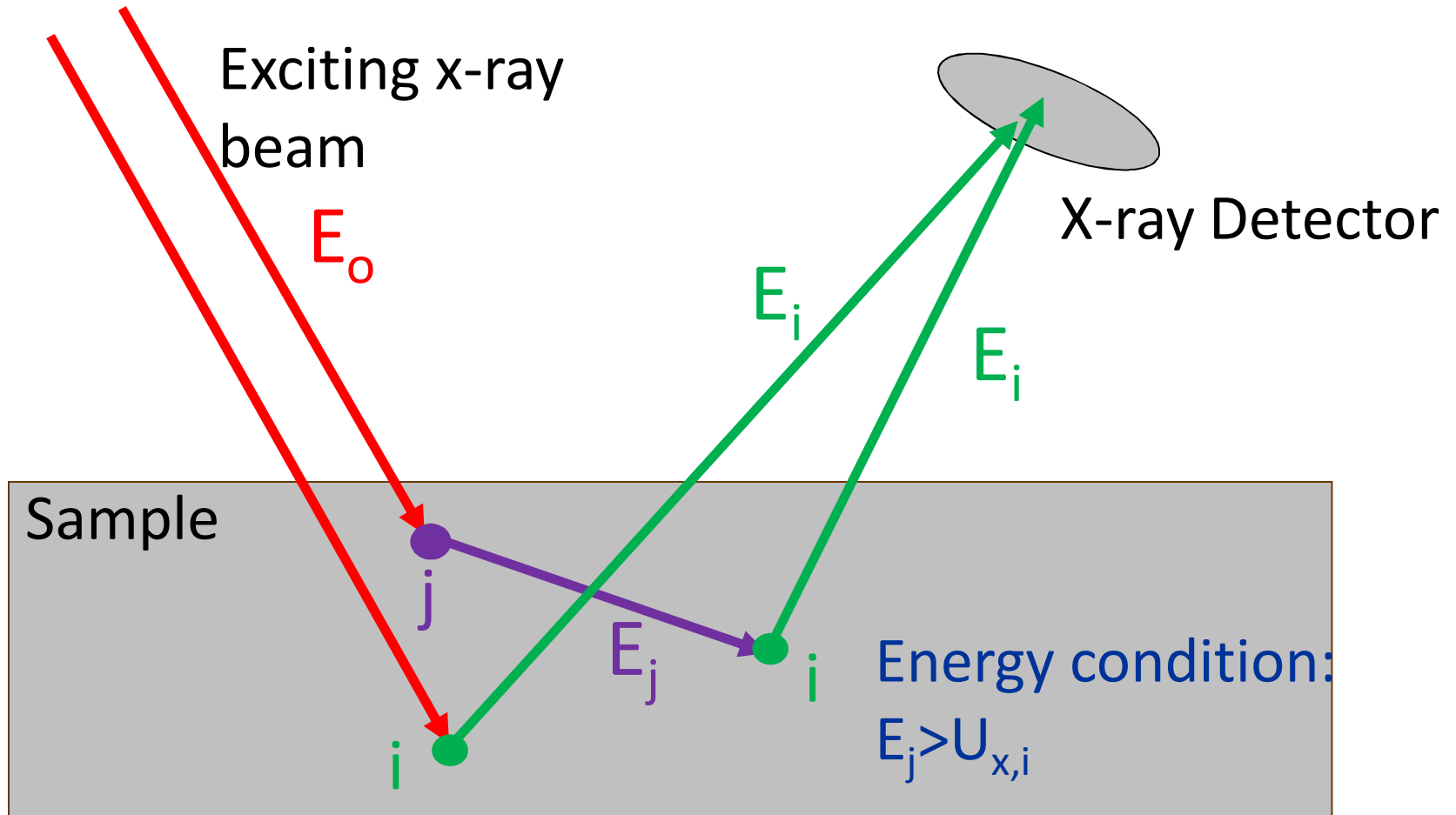
J. Fernandez et al., X-Ray Spectrom. 2013, 42, 189–196

Indirect Enhancement Processes in Fluorescence Emission



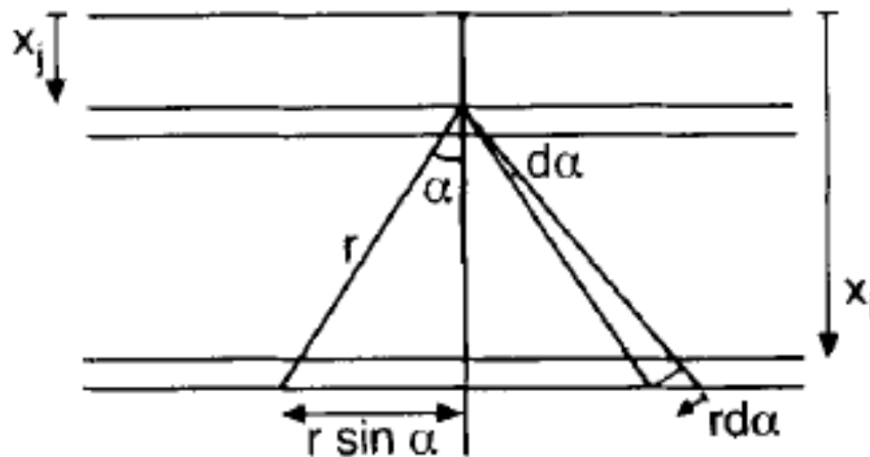
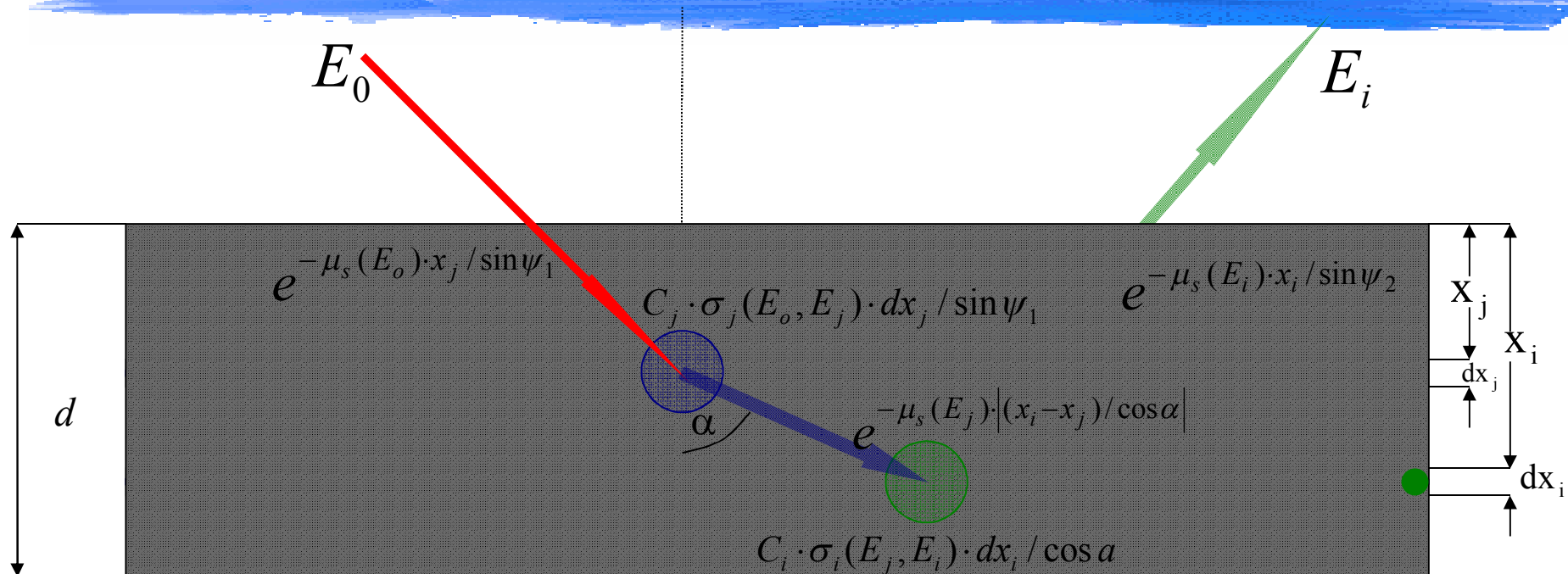
J. Fernandez et al., X-Ray Spectrom. 2013, 42, 189–196

Secondary Fluorescence Enhancement



Element j characteristic x-ray(s) can excite element i characteristic x-rays within the sample volume

Secondary enhancement calculation: Example

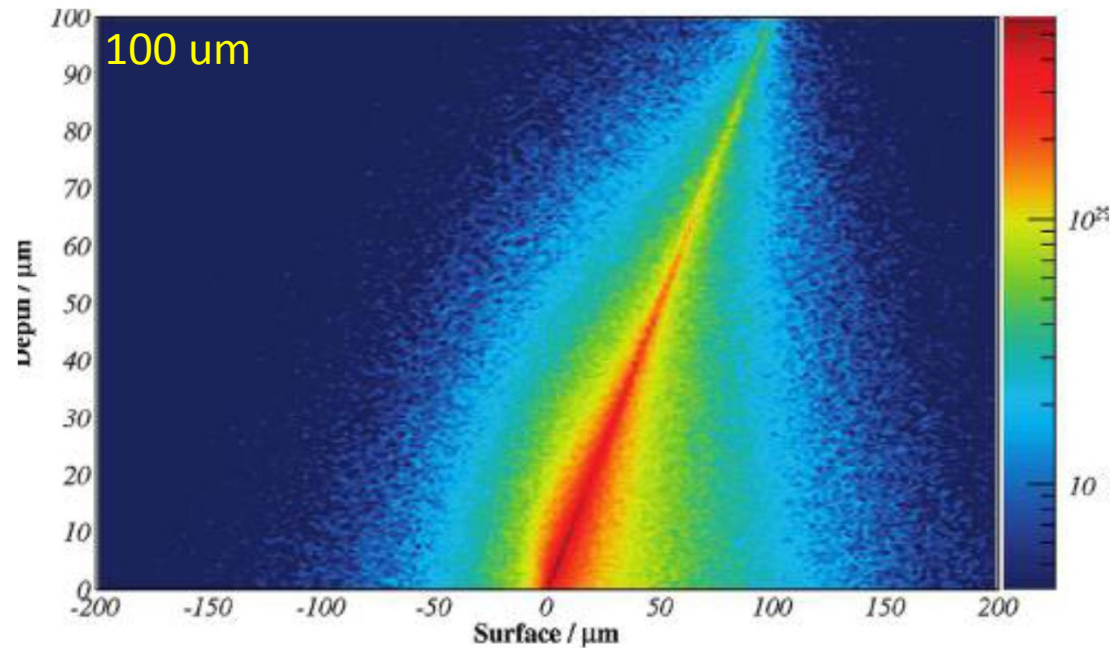


Number of photons emitted per unit area of layer dx_j that reach layer dx_i within the cones with aperture angles $\alpha, \alpha+d\alpha$

$$(2 \cdot \pi \cdot r \cdot \sin \alpha) \cdot (r \cdot d\alpha) \times \frac{1}{4 \cdot \pi \cdot r^2} =$$

$$\frac{1}{2} \cdot \sin \alpha \cdot d\alpha$$

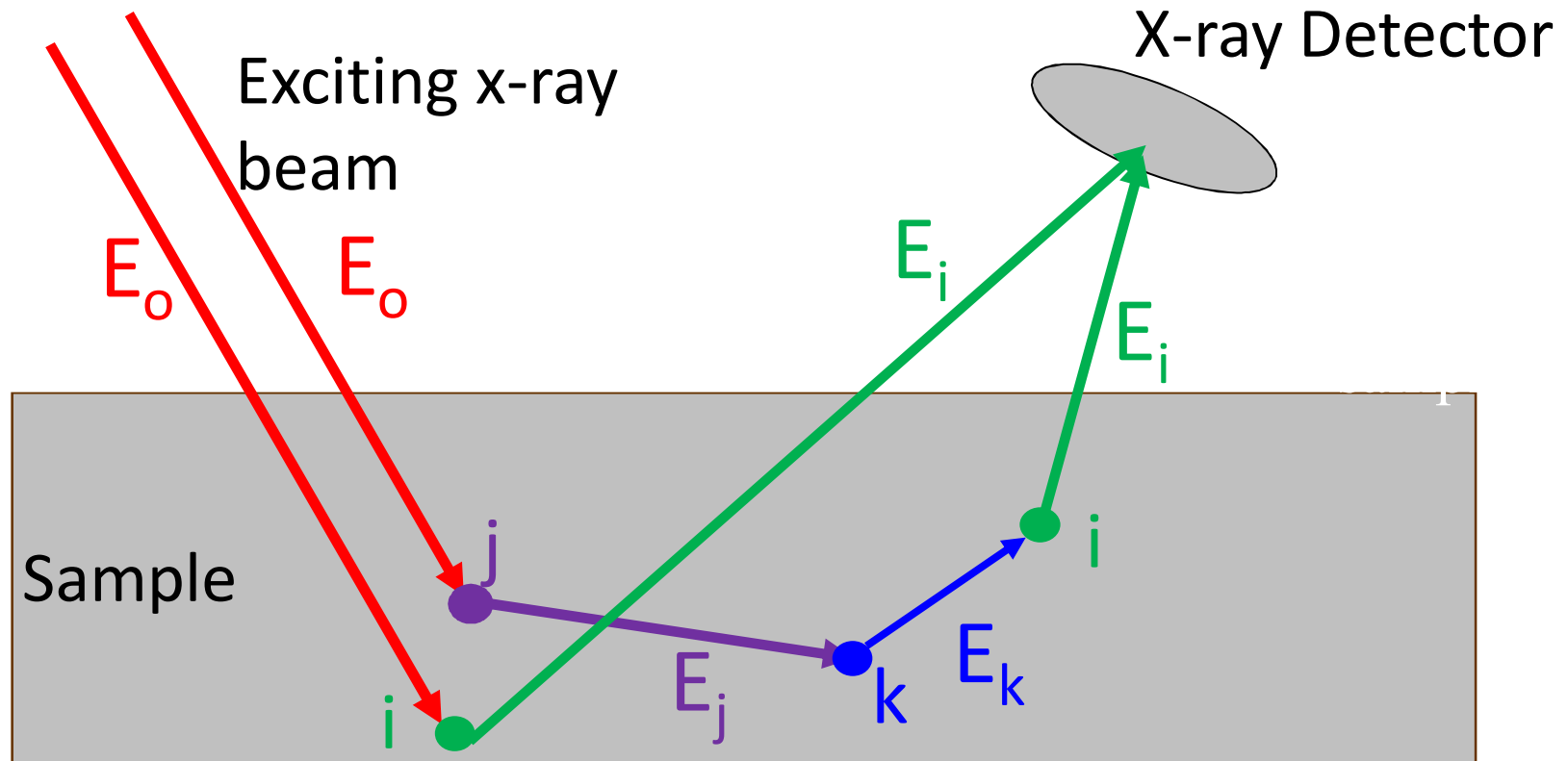
Topology of secondary fluorescence



13 keV, excitation, SiO₂ matrix, 5% Cu, 5% Fe

Sokaras et al, Anal. Chem. 2009, 81, 4946

Tertiary Fluorescence Enhancement



The element j characteristic x-ray(s) can excite element's k characteristic x-ray(s) which consequently can also excite element's i characteristic x-rays

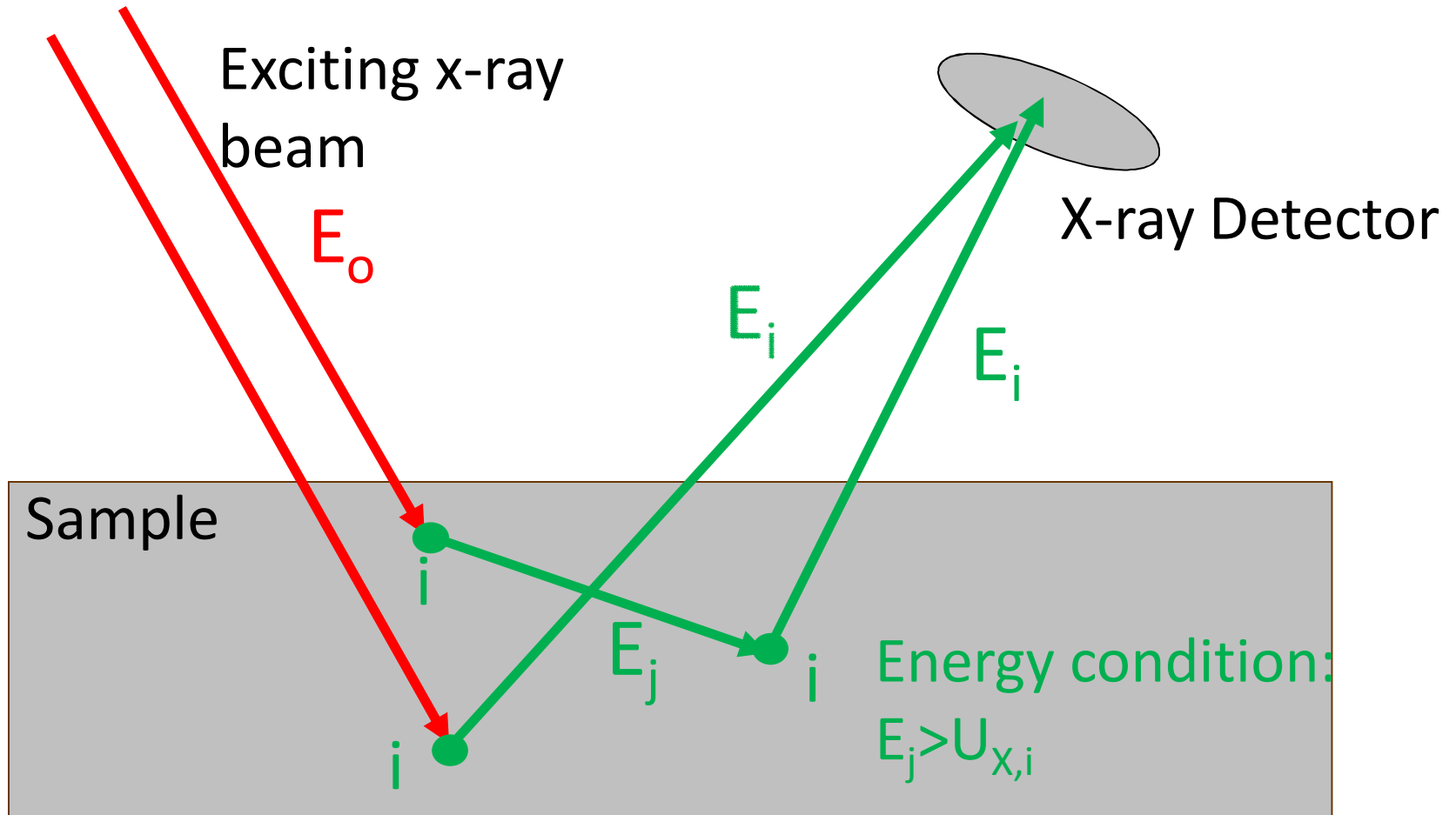
Energy conditions: $E_j > U_{x,k}$ and $E_k > U_{x,i}$

SF Enhancement in Poly-Energetic excitation

Type of Sample	Secondary Fluorescence Mechanism	Am-241 (59.6 keV) Source*	Filtered Rh-tube excitation*
Ag: 92.5% Cu: 7.5 %	Ag-K to Cu	1.57	0.29
Au: 88.3 % Ag: 8.5 % Cu: 3.1 %	(Ag-K+Au-L) to Cu	0.82	0.55
	Ag-K to Au	6.6e-2	1.4e-2
Cu: 80 % Pb: 10 % Sn: 10 %	(Sn-K + Pb-L) to Cu	0.22	7.8e-2
	Sn-K to Pb	0.11	1.6e-2

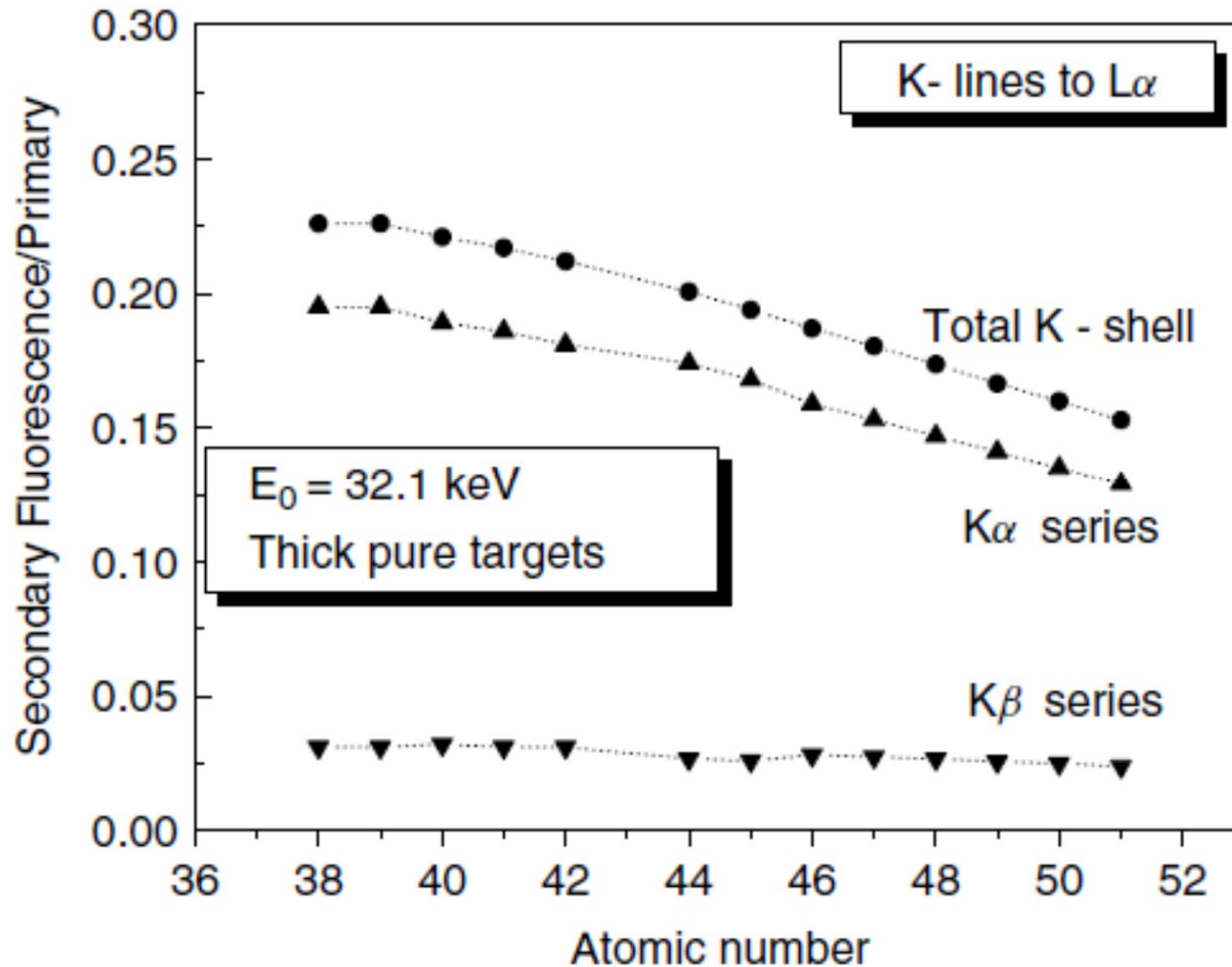
* Including ternary contribution

Self-element SF Enhancement (special case)



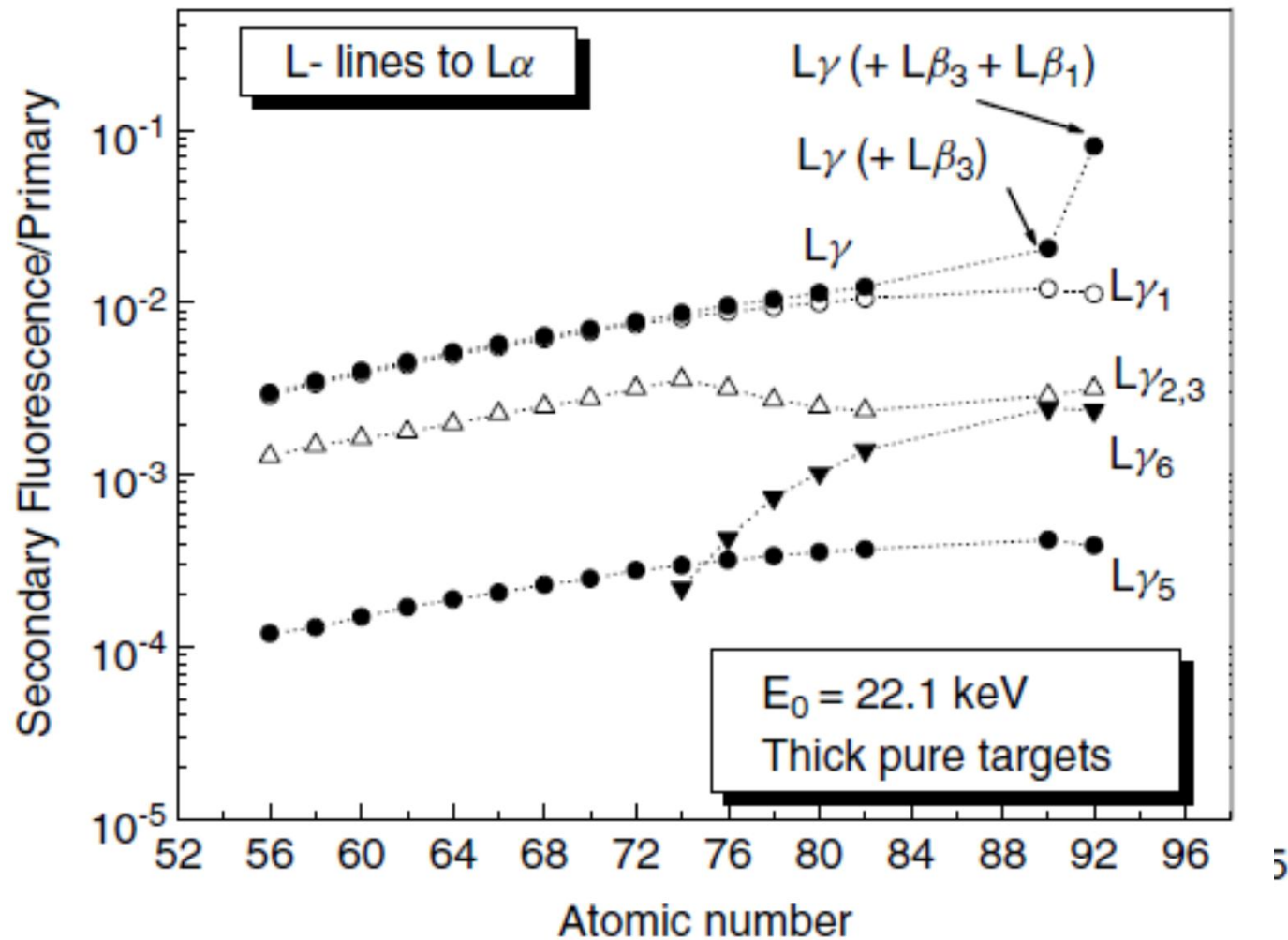
Element i characteristic x-ray(s) can excite different series of characteristic X-rays of the same element i within the sample volume; for example K to L, L to M lines

Self-element SF Enhancement (special case)



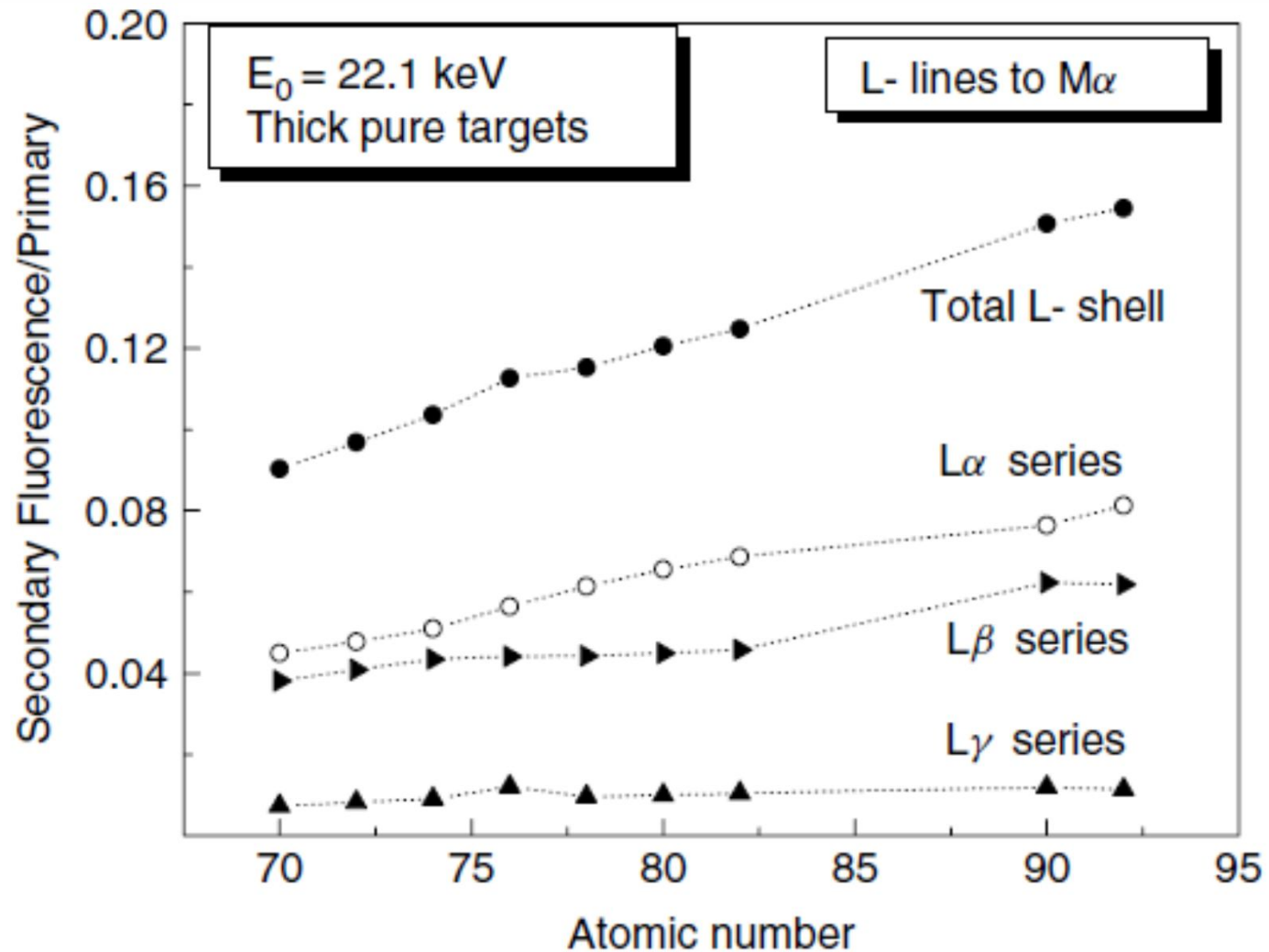
A.G. Karydas et al., X-Ray Spectrom. 2005; 34: 426–431

Self-element SF Enhancement (special case)



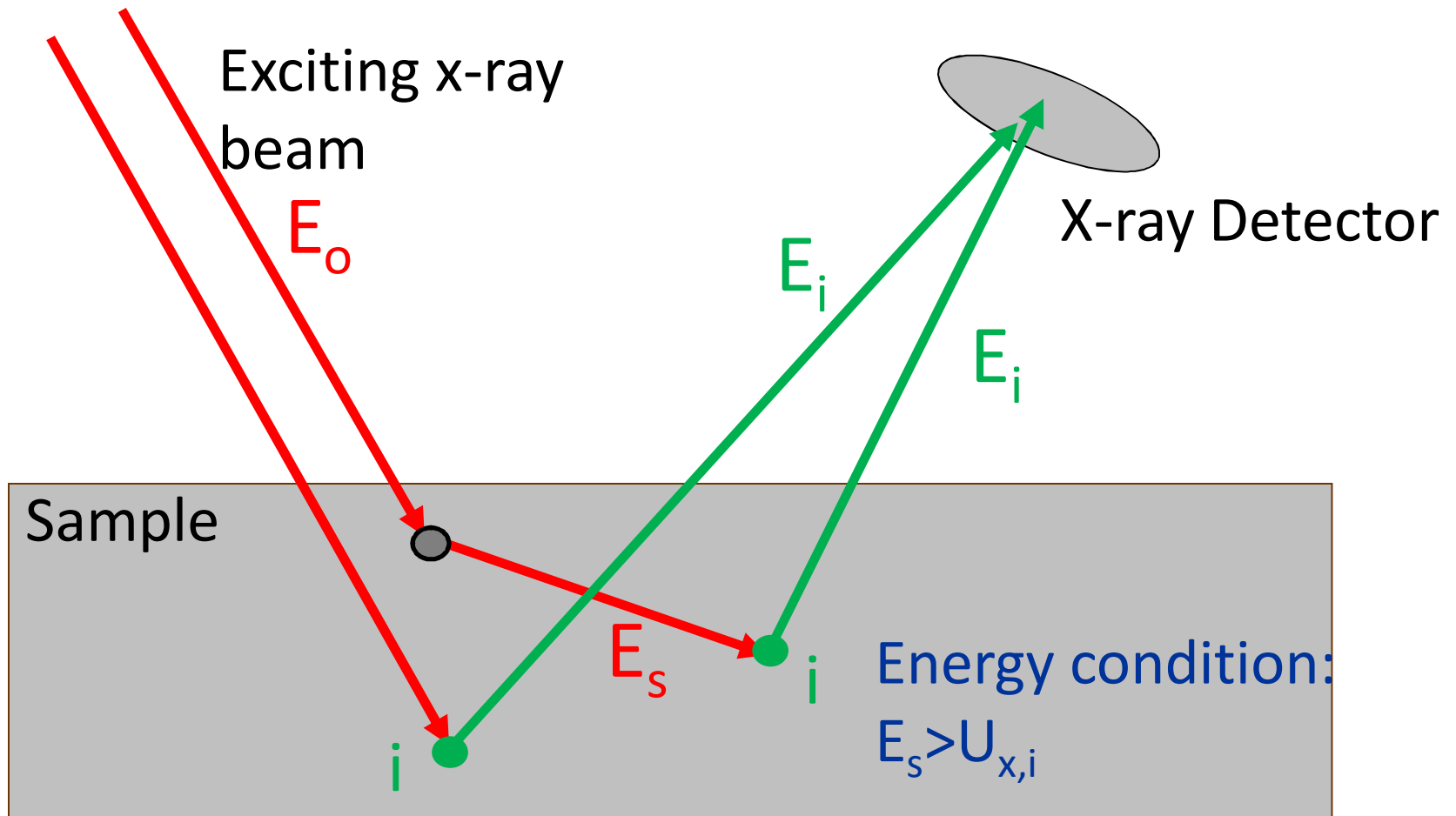
A.G. Karydas et al., X-Ray Spectrom. 2005; 34: 426–431

Self-element SF Enhancement (special case)



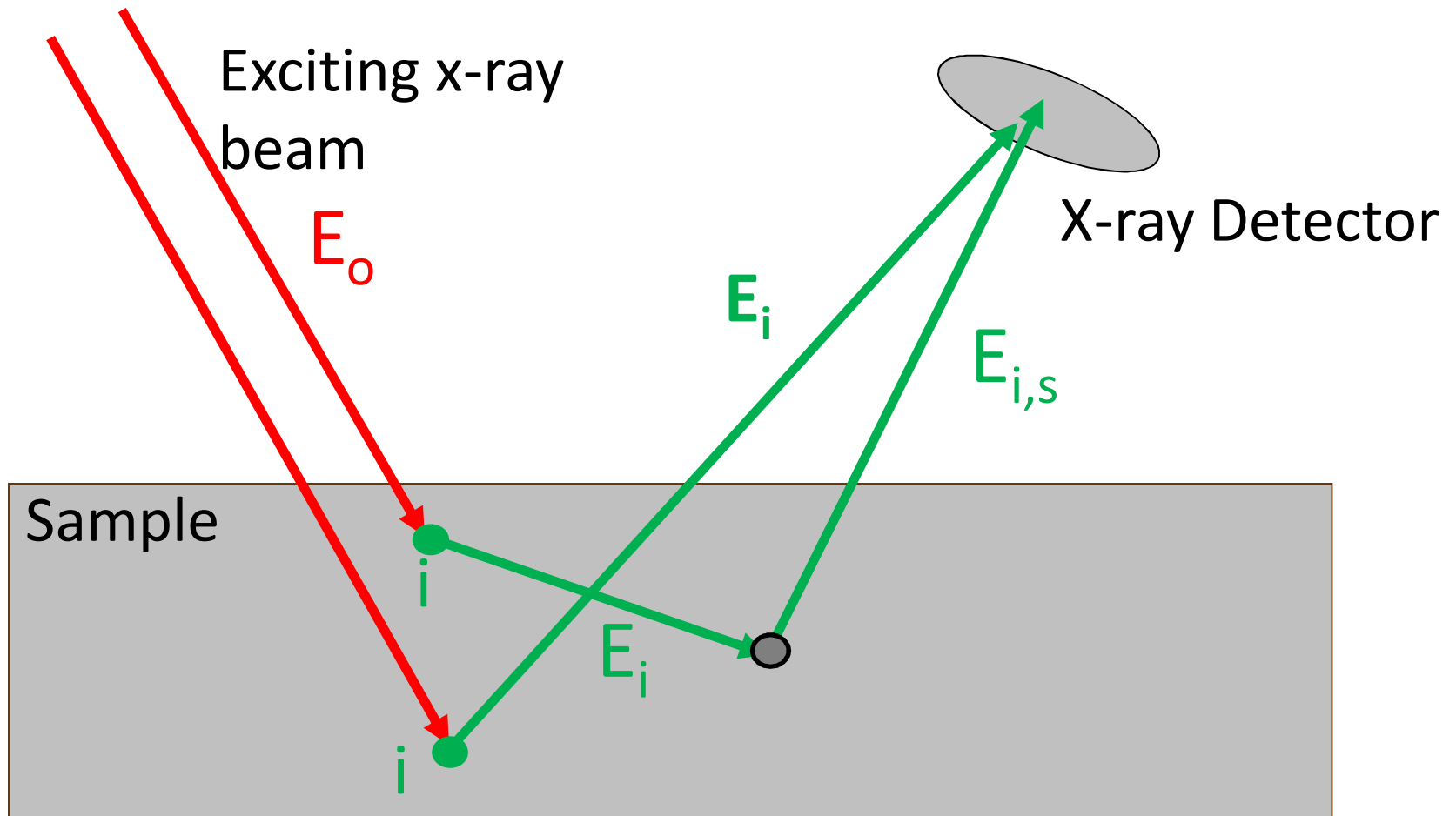
A.G. Karydas et al., X-Ray Spectrom. 2005; 34: 426–431

Secondary Scattering Enhancement (Beam)



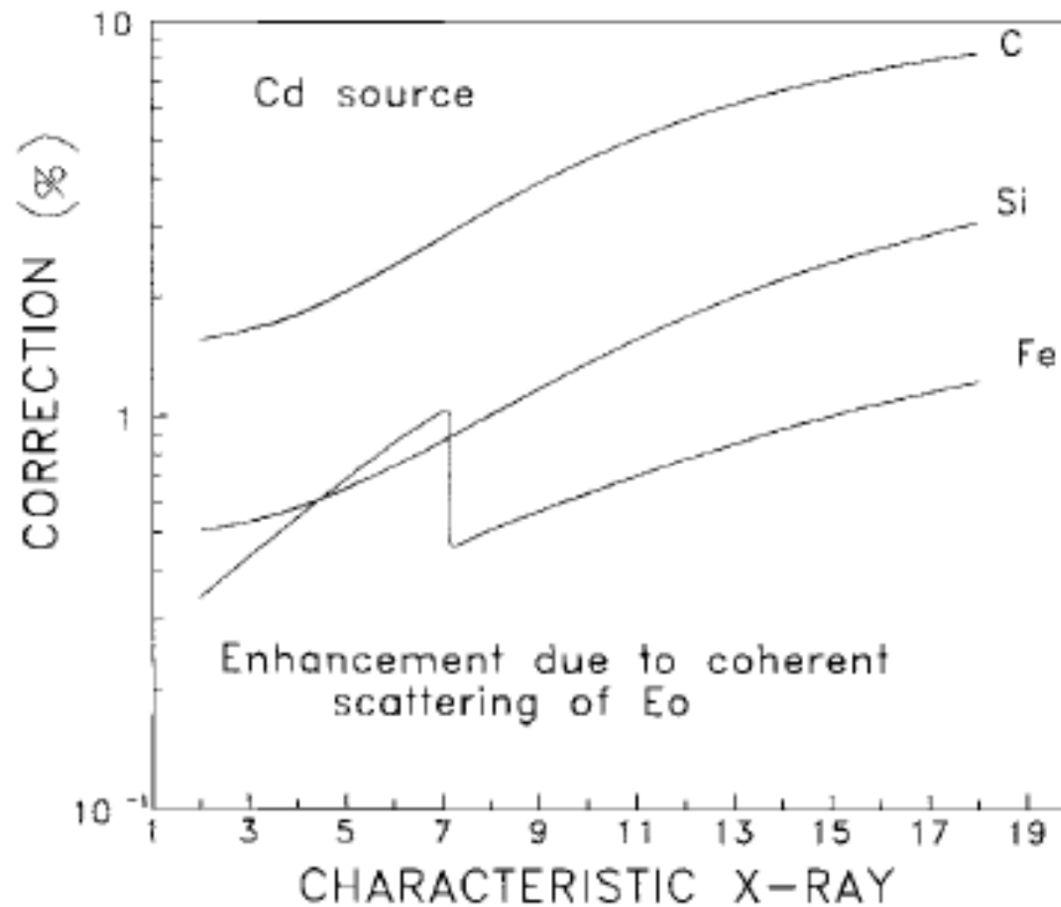
Incident beam after encountering elastic/inelastic scattering at one produces photoionization of an element i in another sample position volume

Secondary Scattering Enhancement (Fluo)



Element a characteristic x-ray after elastic/inelastic scattering within the sample volume are directed to the detector

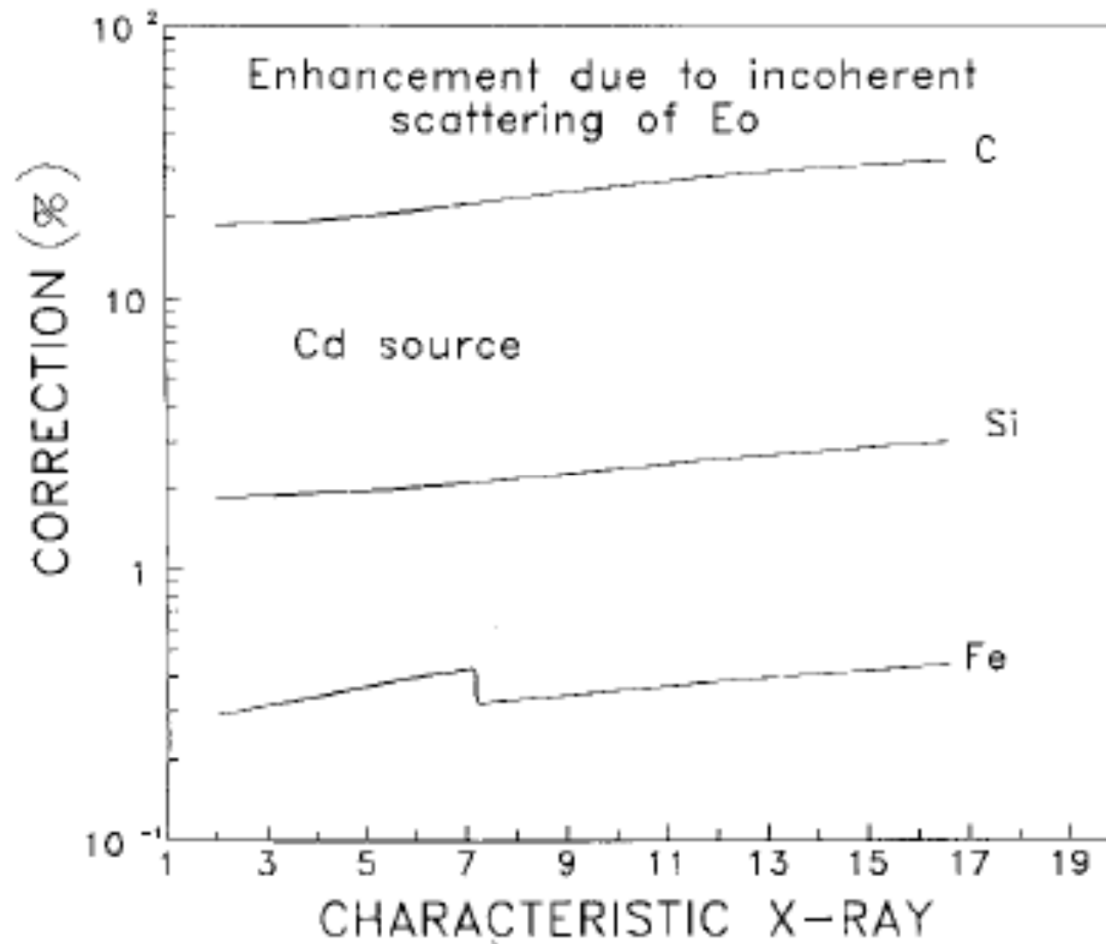
Secondary Enhancement due to Scattering



Karydas, Paradellis, X-Ray Spectrom. 1993; 22: 208

Tirao, Stutz, X-Ray Spectrom. 2003; 32: 13–24

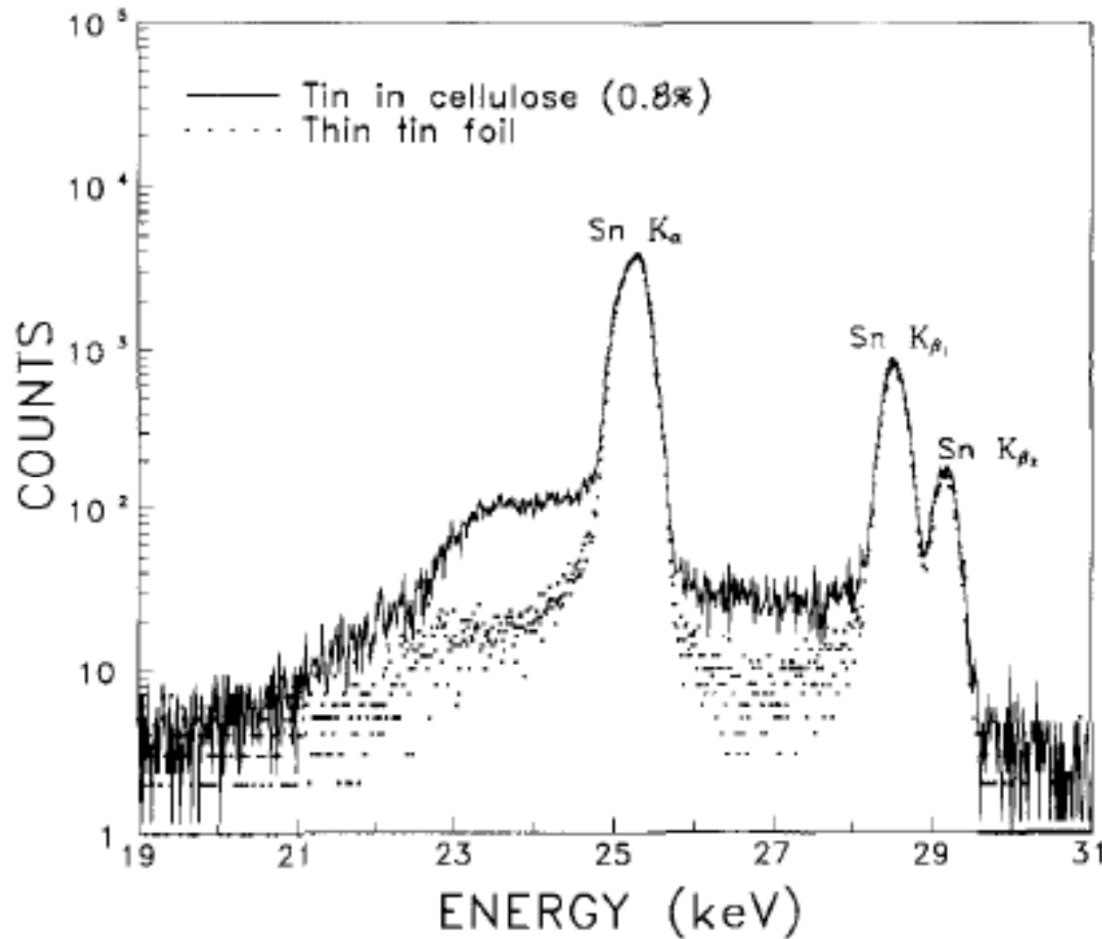
Secondary Enhancement due to Scattering



Karydas, Paradellis, X-Ray Spectrom. 1993; 22: 208

Tirao, Stutz, X-Ray Spectrom. 2003; 32: 13-24

Secondary Enhancement due to Scattering

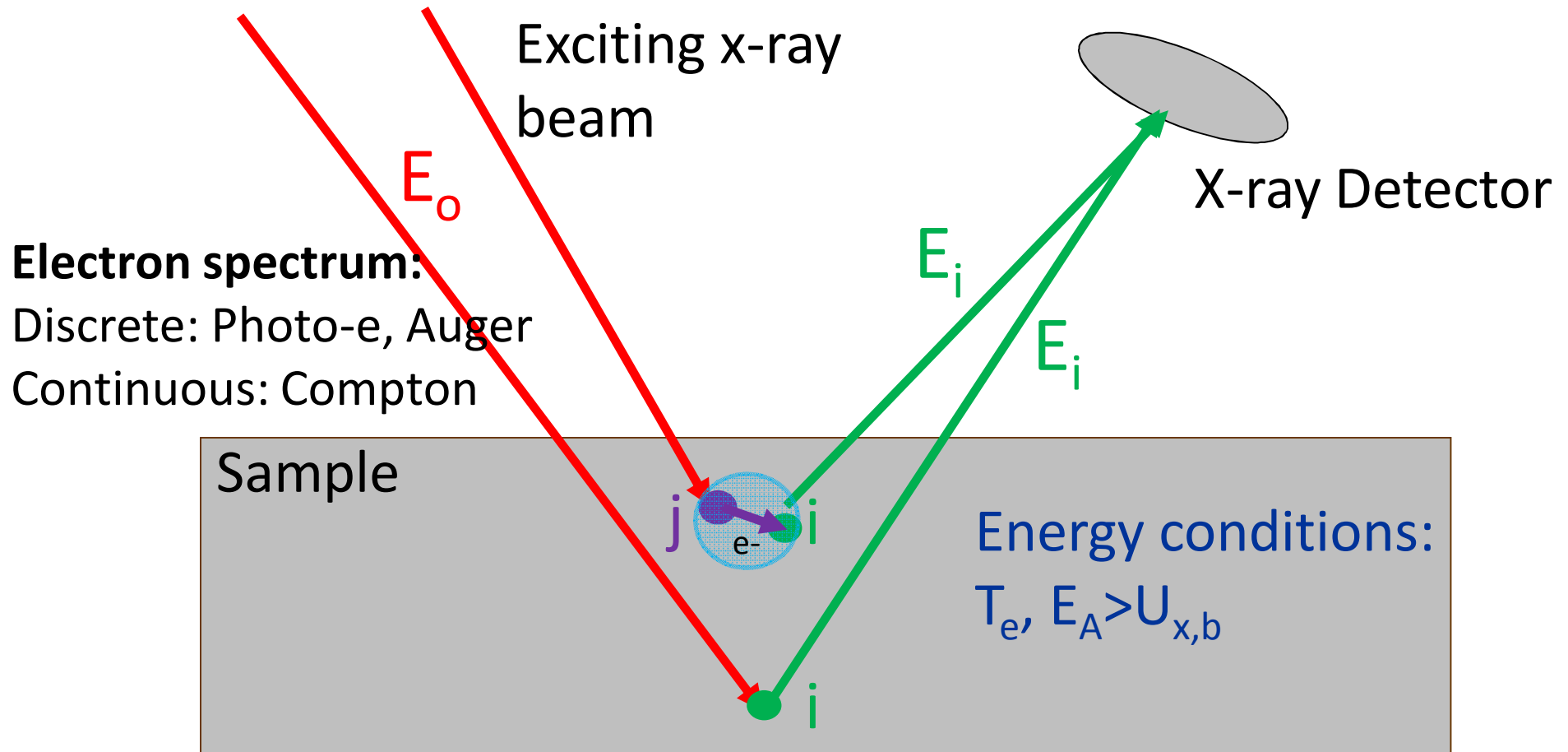


Effect on
spectrum!

Karydas, Paradellis, X-Ray Spectrom. 1993; 22: 208

Tirao, Stutz, X-Ray Spectrom. 2003; 32: 13–24

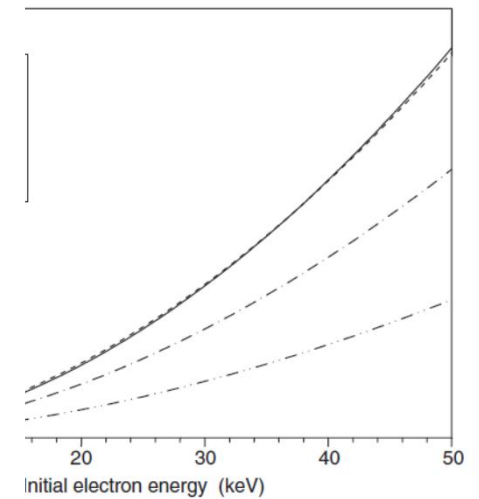
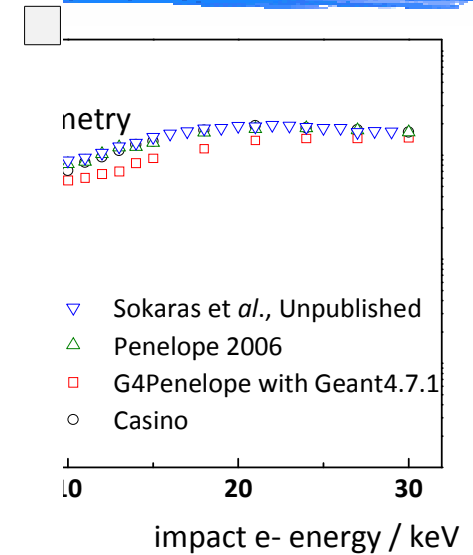
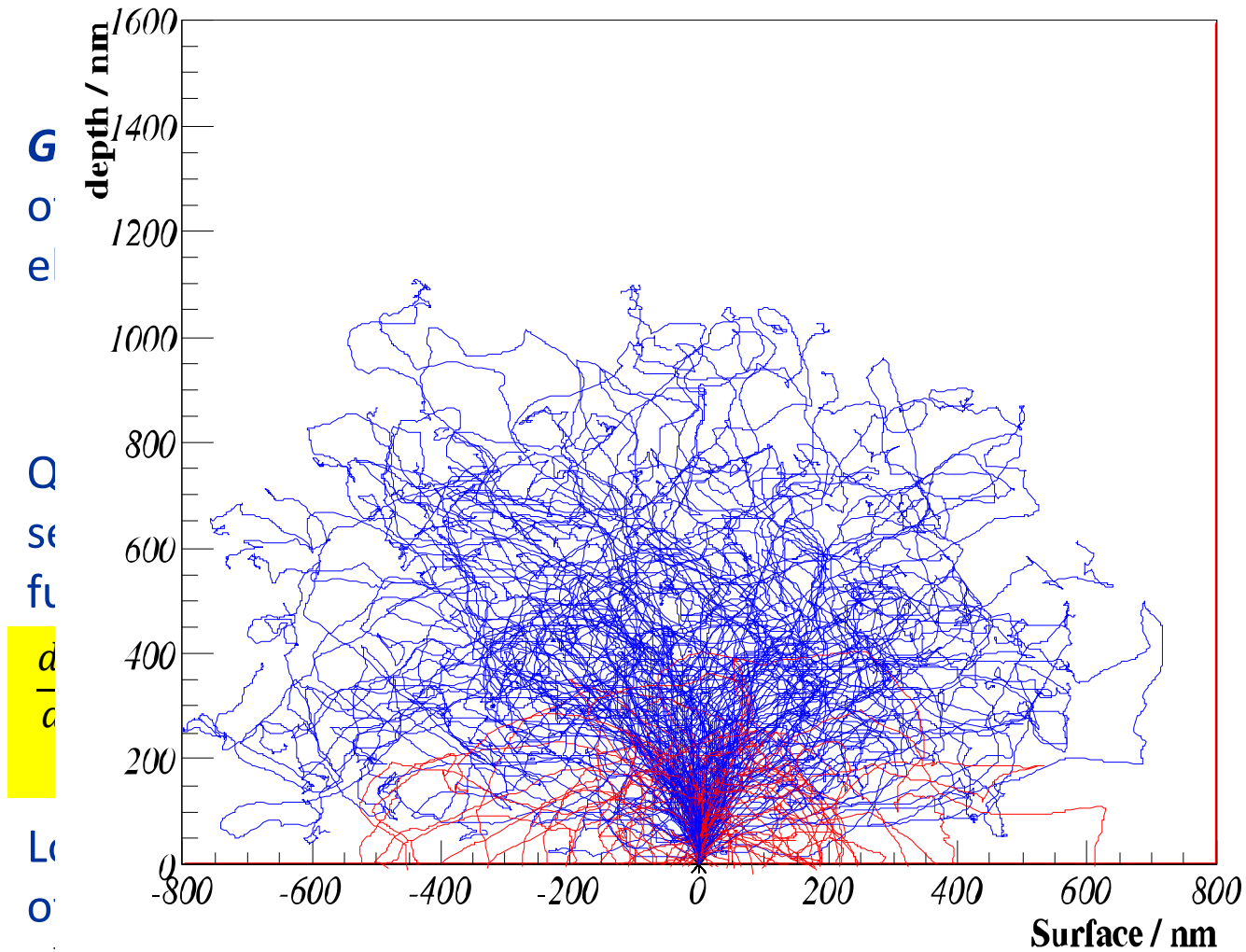
Photo-/Auger/Compton e^- Indirect Fluorescence Enhancement



Ejected electrons from the atoms of element j can ionize an inner shell of element i

Ionization induced by electrons

Stochastic movement of electrons (20 keV on Fe)



Ionization induced by electrons

Stochastic movement of electrons (20 keV on Fe)

$$n_i(E_o) = \frac{N_A \rho W_i}{A_i} \int_{E_0}^{E_{Edge,i}} Q_i(E) \frac{1}{dE/ds} dE$$

Green and Cosslett expression for the number of photons emitted by interaction with a single electron of initial kinetic energy E_0

$$Q_{ip}(E) = 6.51 \times 10^{-20} \frac{Z_{subshell,i}}{E_{Edge,i}^2} b \frac{\ln(cU)}{U} \quad (cm^2)$$

$Q_i(E)$ and dE/ds are the inner shell ionization cross-section and the stopping power (energy loss function), respectively, of electrons in a material

$$\frac{dE}{ds} = -\frac{\rho}{J'} \sum_k \frac{W_k Z_k}{A_k} \frac{1}{1.18 \times 10^{-5} \sqrt{E/J'} + 1.47 \times 10^{-6} (E/J')}$$

Love et al. expression for stopping power of electrons

$$J_k = 0.0115 Z_k \quad (keV) \quad \text{the mean ionization potential}$$

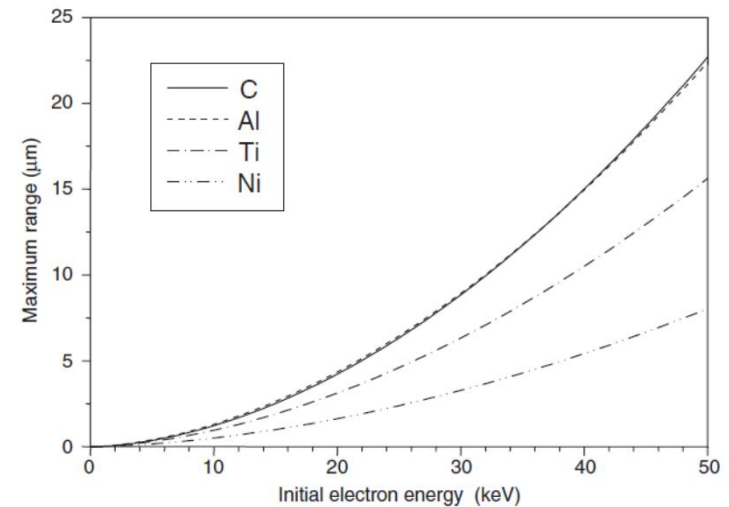
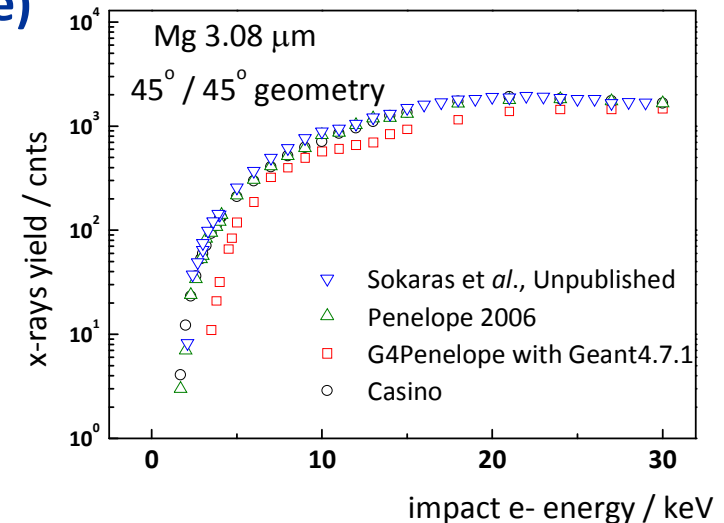
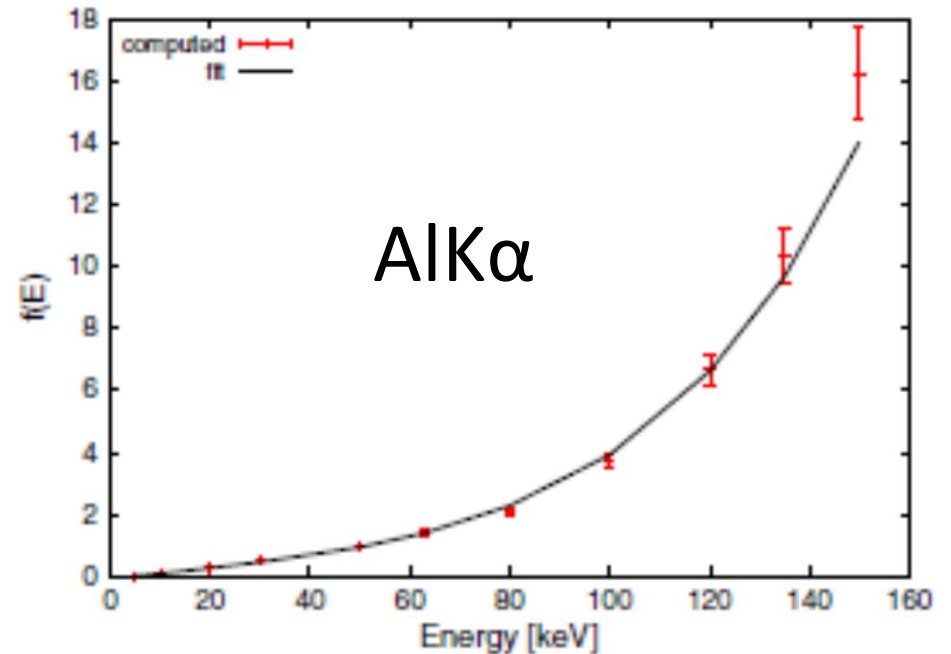
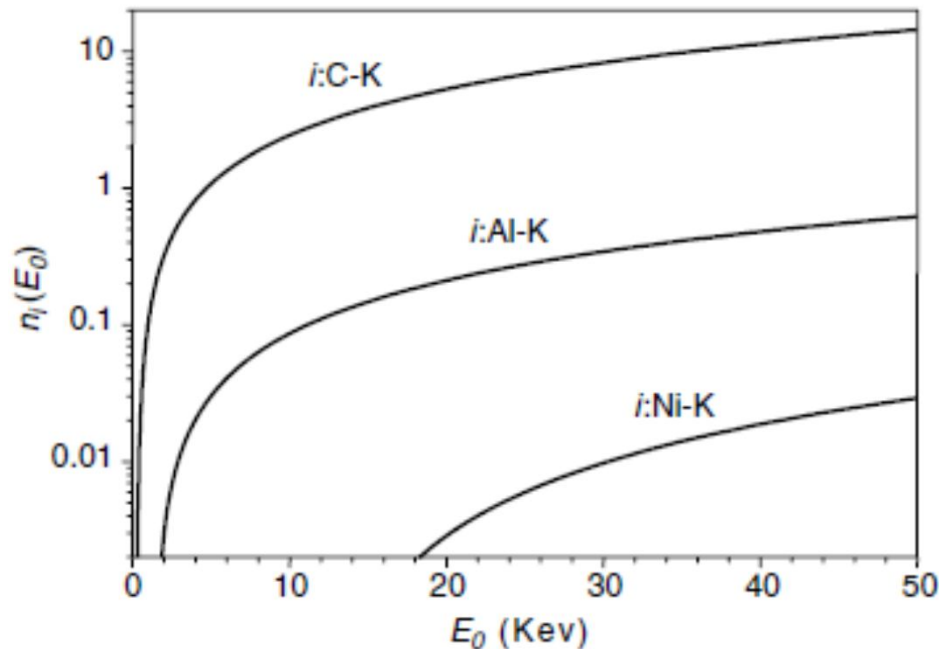


Photo e⁻ Fluorescence Enhancement

$$N_{i,photo-electron} = G_i C_i \sum_j \int_{E=E_{Edge,j}}^{E=E_{max}} \frac{N_0(E) \tau_j n_i(E - E_{Edge,j}) dE}{\mu^*}$$

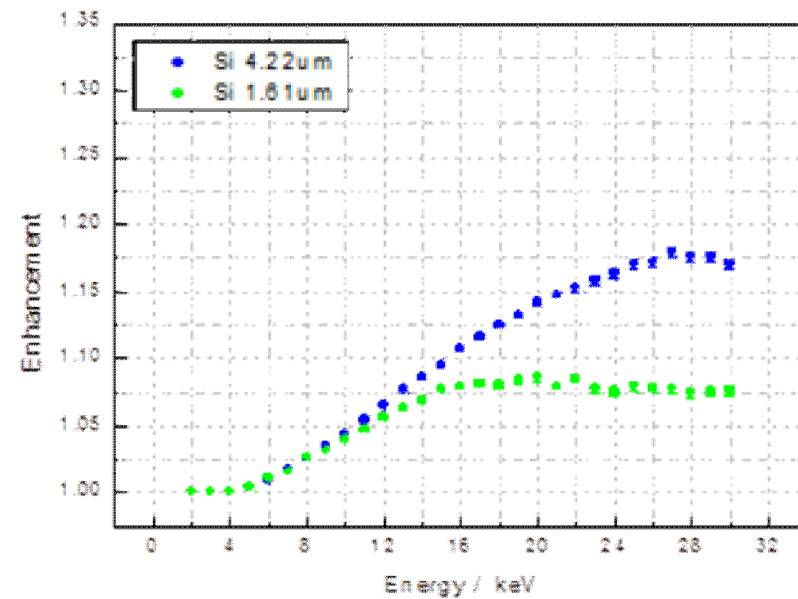
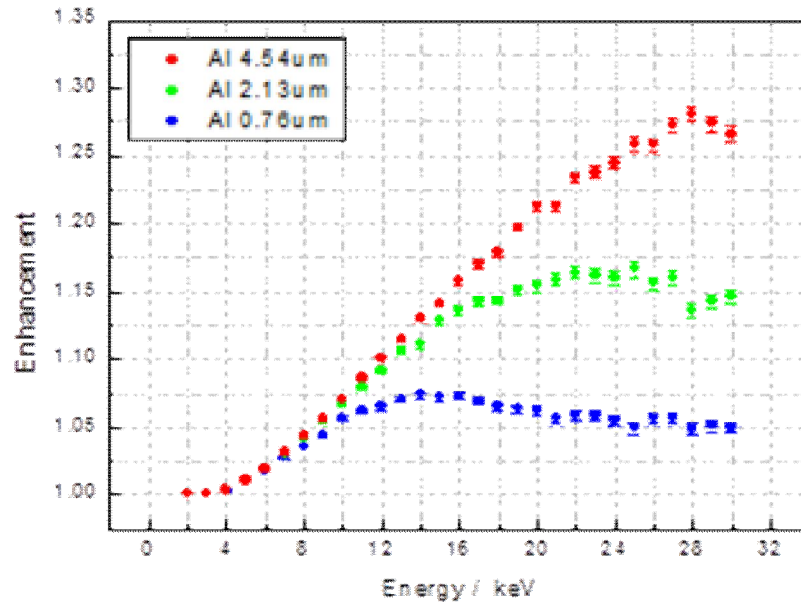
Increases when exciting beam energy is far away from absorption edge of light elements



N. Kawahara in Handbook of Practical X-Ray Fluorescence Analysis, by B. Beckhoff B. Kanngiesser, N. Langhoff, R.Wedell, H.Wolff, (Eds.)

J. Fernandez et al., X-Ray Spectrometry 2013, 42, 189–196

Photo e⁻ Fluorescence Enhancement



Monte Carlo calculations of phot-e enhancement:
Al (4.54 μm, 2.13 μm, 0.76 μm) and Si (4.22 μm, 1.61 μm)
Casnati parameterization for electron ionization cross sections

D. Sokaras et al., unpublished

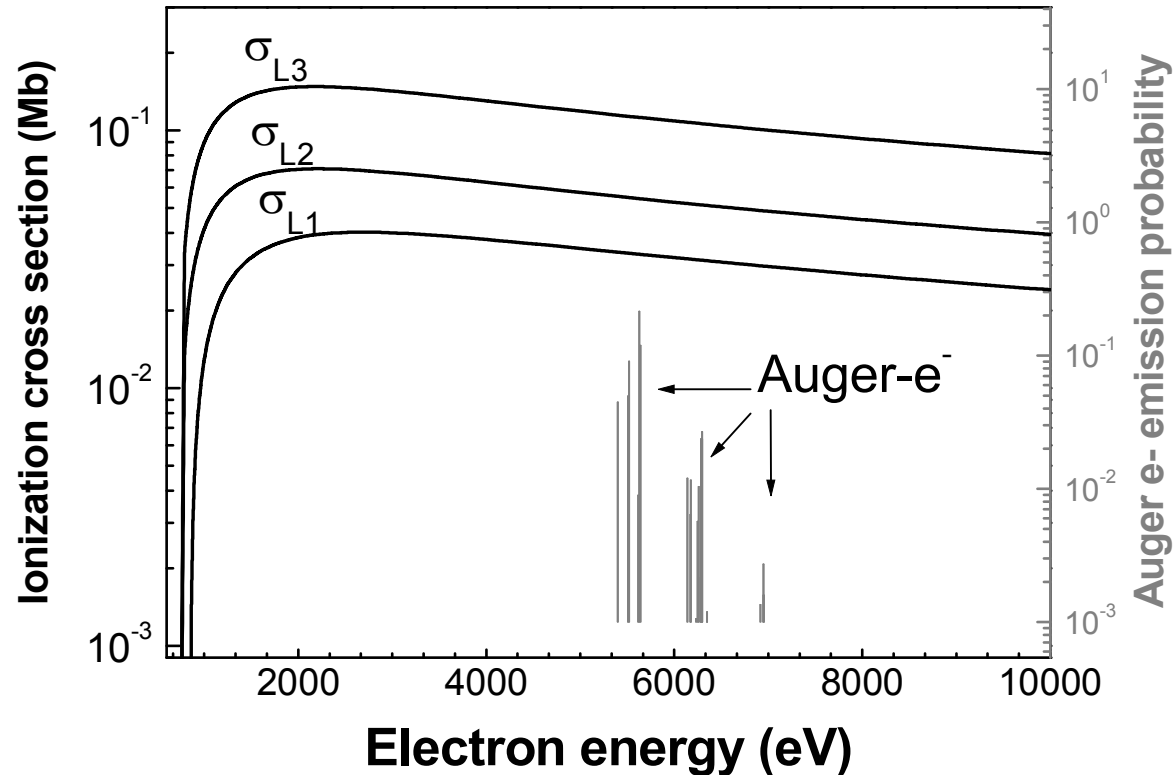
Auger e⁻ Fluorescence Enhancement

$$N_{i,Auger-electron} = G_i C_i \sum_j \int_{E=E_{Edge,j}}^{E=E_{max}} \frac{N_0(E) \tau_j (1 - \omega_i) \sum_{\kappa} n_i(E_{Auger-electron,jk})}{\mu^*} dE$$

- **Important:** When a light element analyte is embedded in a heavy element matrix.
- The Auger-electrons from the matrix elements can excite light element fluorescence.
- Example: When carbon in steel is analyzed, a Fe KLL Auger-electron with a kinetic energy of 6.3 keV can excite multiple carbon K-shells

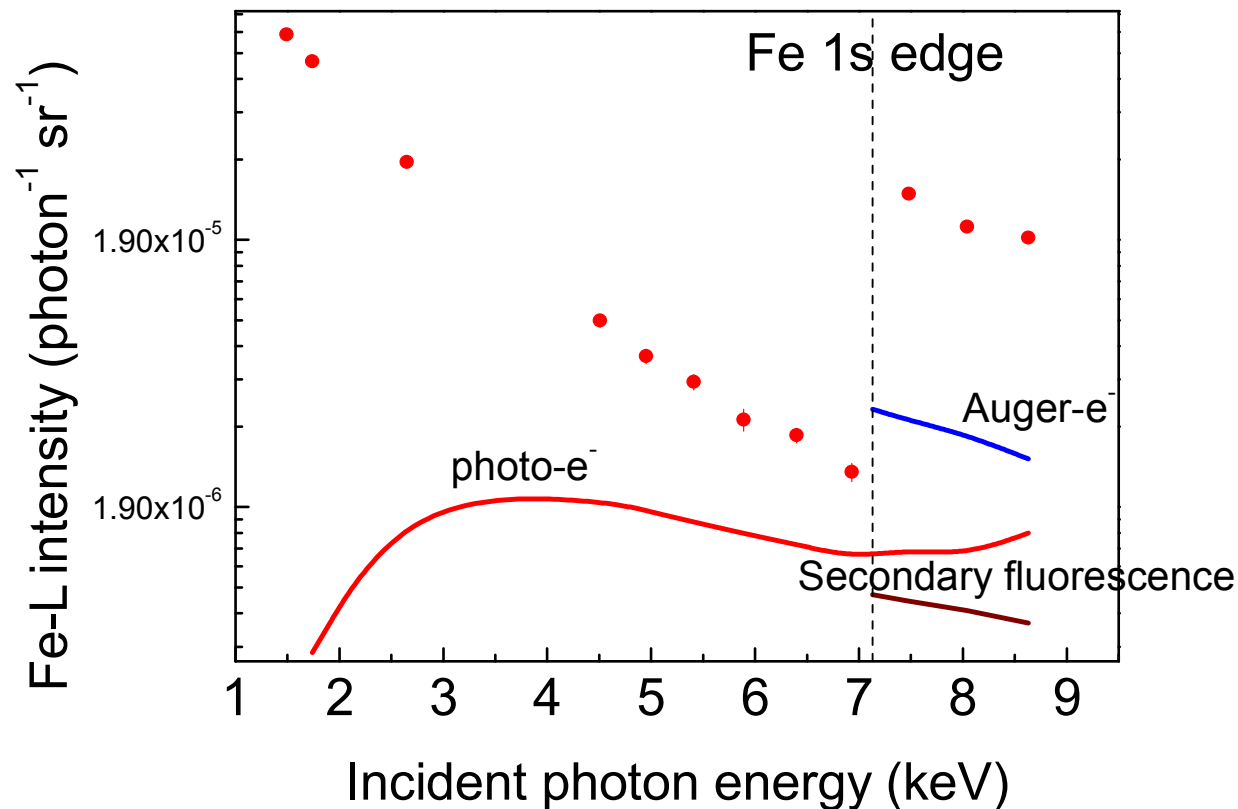
Secondary electron induced ionizations

Example: Thick Fe target



- L-shell photoelectrons: $T_e = E_o - U_{Li}$,
- Auger-electrons (when $E_o > U_K$)

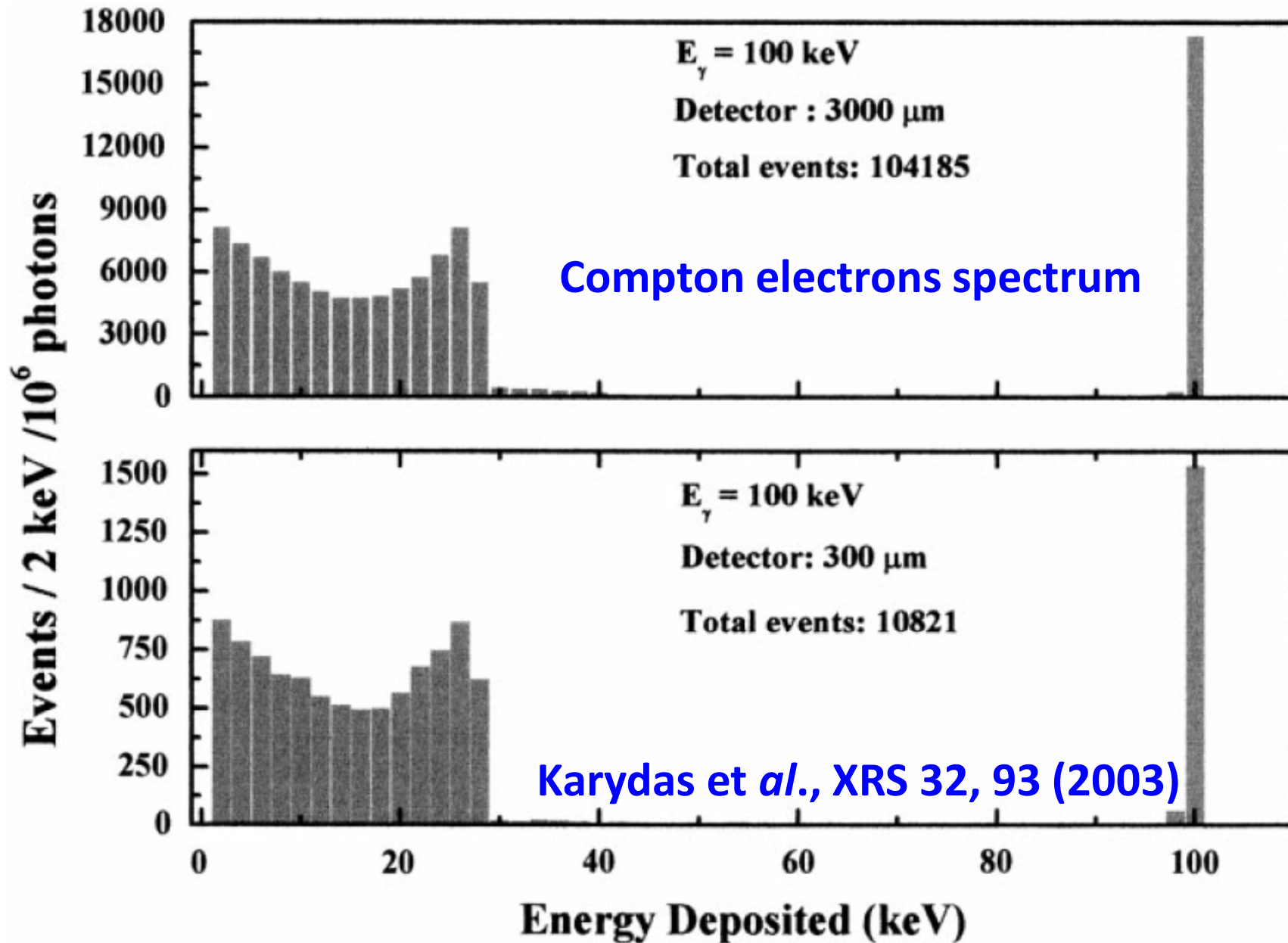
Relative e- enhancement to Fe-L α excitation in the case of a Fe pure target



Bulk metallic Fe, Unpolarized incident radiation

Sokaras et al., Phys. Review A 83, 052511 (2011)

Compton electrons Fluorescence Enhancement



Compton electrons Fluorescence Enhancement

Thomas-Fermi model for the incoherent scattering function

$$\frac{\partial_a \sigma_{incoh}}{\partial \Omega} = \frac{\partial_c \sigma_{KN}(E_0, E', \theta)}{\partial \Omega} ZS(\alpha, \theta, Z)$$

$$S(v) = 1 - \exp(-4.88v^{0.856})$$

$$v = \frac{2}{3} \frac{137}{Z^{2/3}} a \sin(\theta/2)$$

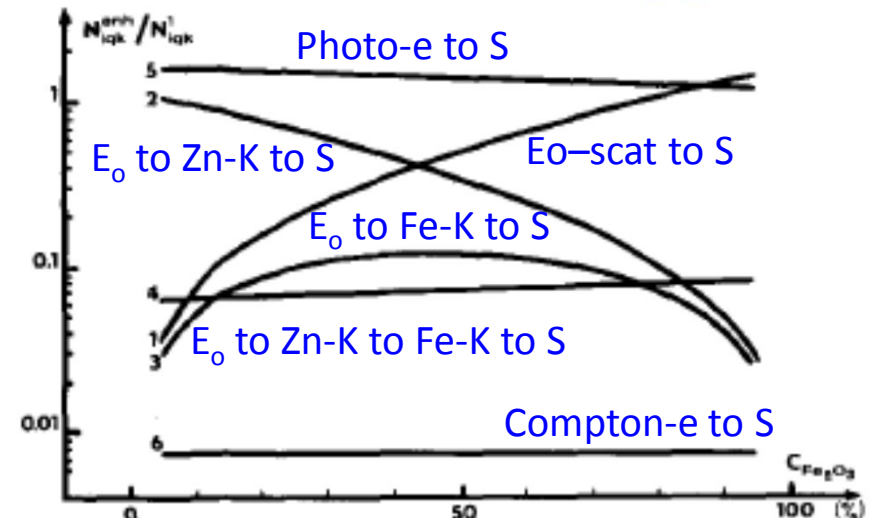
$$\alpha = \frac{E_0}{m_c c^2}$$

Energy distribution of Compton electrons

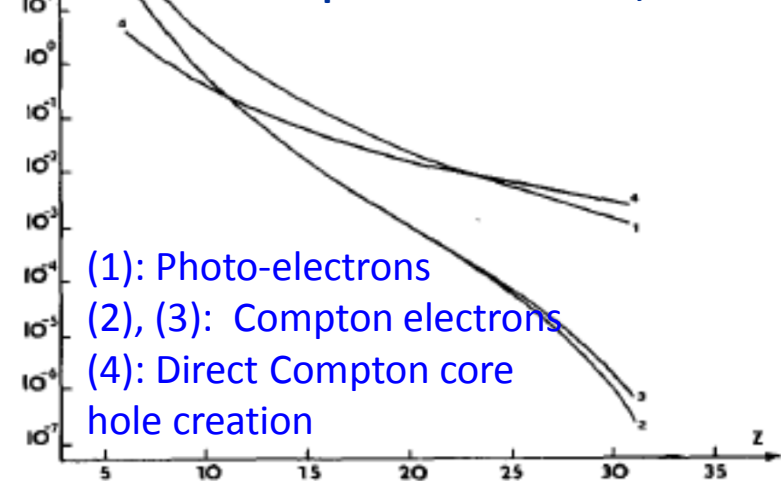
$$\begin{aligned} & \frac{\partial_a \sigma_{incoh}}{\partial E} \\ &= 2\pi Z r_0^2 \frac{m_c c^2}{E_0^2} \left[\frac{E_0^2 E_0 E + E^2}{E_0(E_0 - E)} + \left(1 - \frac{m_c c^2 E}{E_0(E_0 - E)} \right) \right] \\ & \left\{ 1 - \exp \left[-1.11766 \times \left(\frac{E_0}{Z^{2/3}} \right) \sqrt{\frac{m_c c^2 E}{2E_0(E_0 - E)}} \right] \right\} \end{aligned}$$

K. Stoev, J. Phys. D: Appl. Phys. 25 (1992) 131-138

Exciting beam : 59.6 keV, Sample: Fe₂O₃ + ZnS

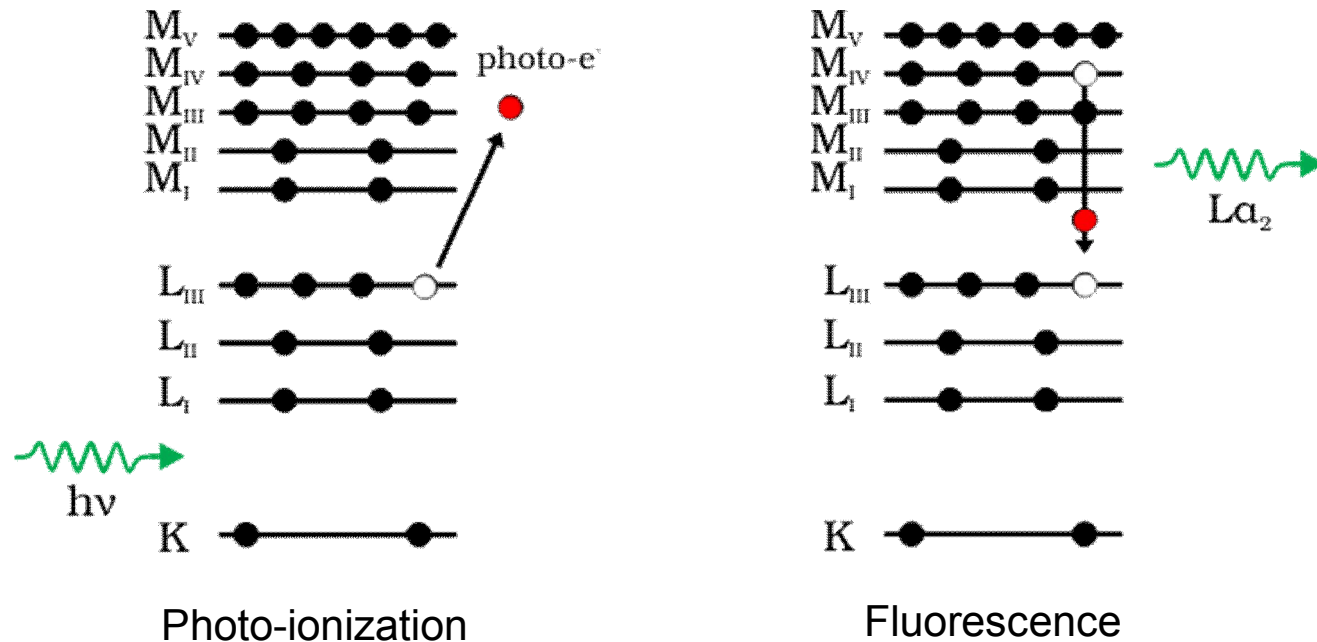


Exciting beam : 59.6 keV, Sample: Pure element, Z



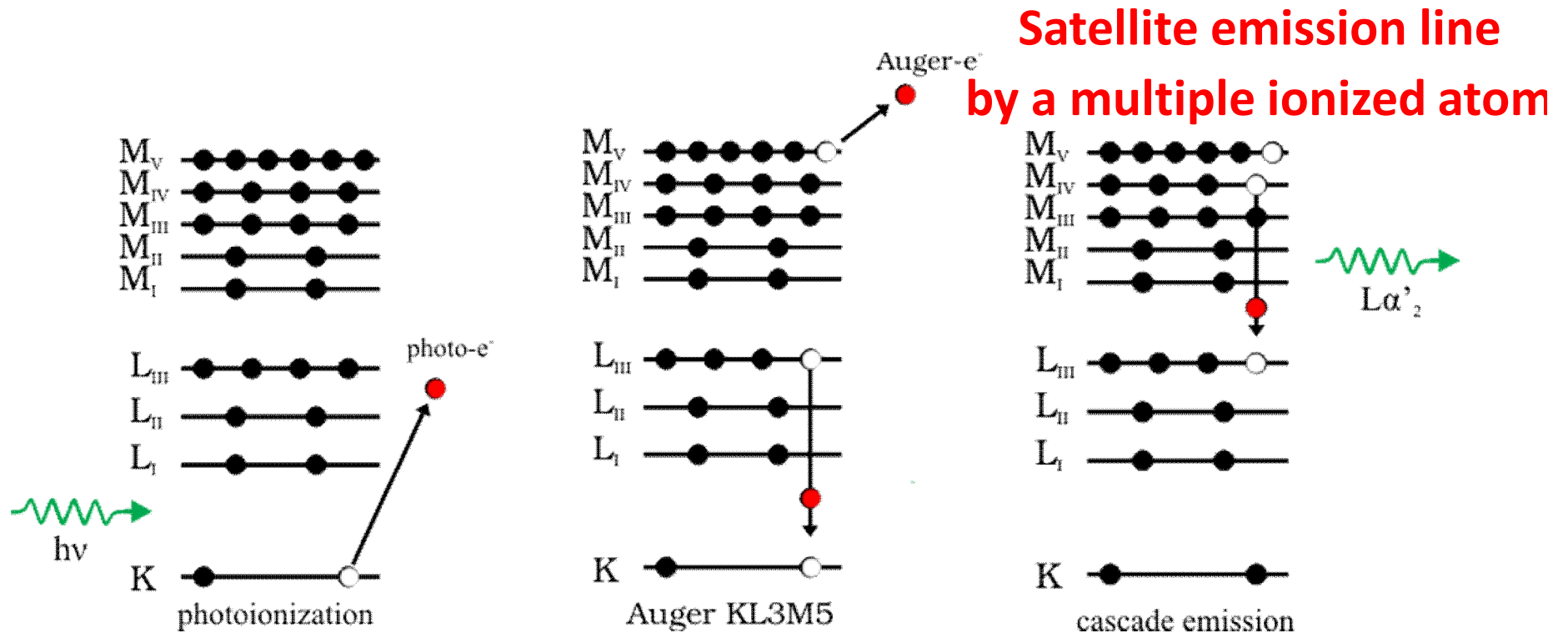
- (1): Photo-electrons
- (2), (3): Compton electrons
- (4): Direct Compton core hole creation

De-excitation processes for inner-shell ionized atoms. Diagram L-emission



Emission of a diagram line

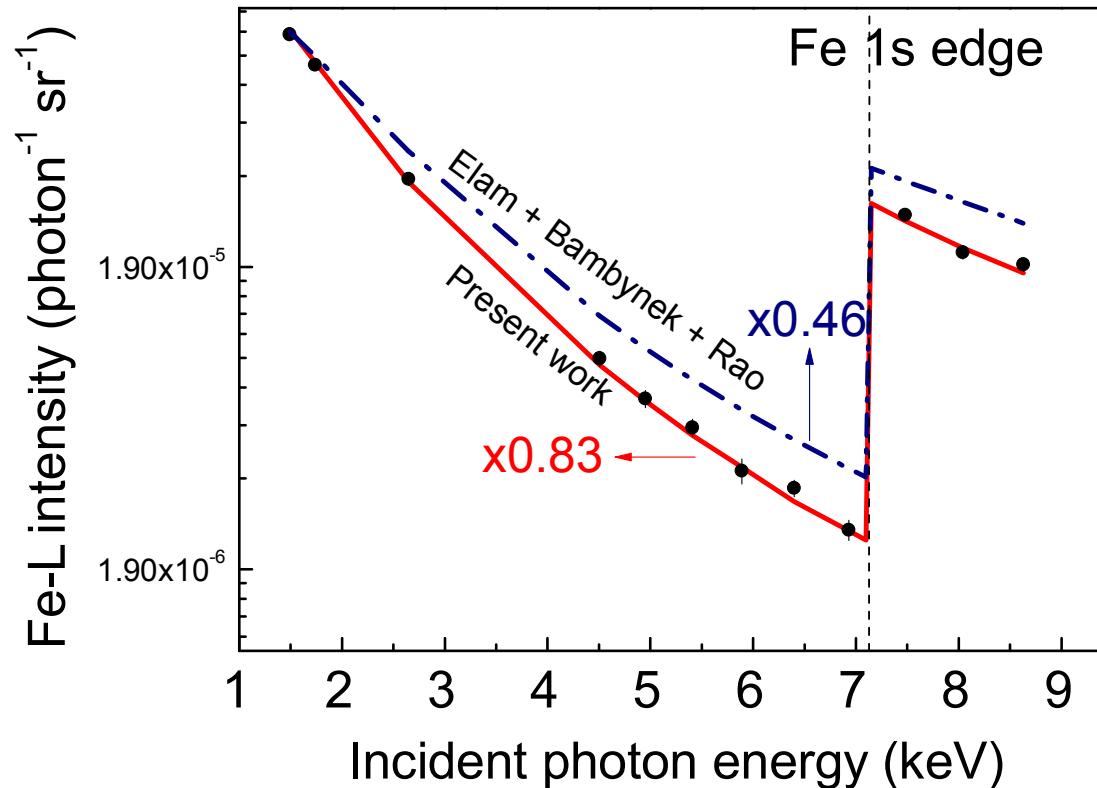
Cascade L X-ray emission



Cascade Emission: X-ray emission due to relaxation of an **indirectly** vacancy created by the relaxation of innermost shell and **not** due to a direct ionization.

Fe-L cascade effect

Bulk metallic Fe, Unpolarized incident radiation



Sokaras et al., Phys. Review A 83, 052511 (2011)

T. Schoonjans et al, SAB, B66, (2011) 776

Fluorescence cross sections include full cascade effect due to radiative and non radiative probabilities

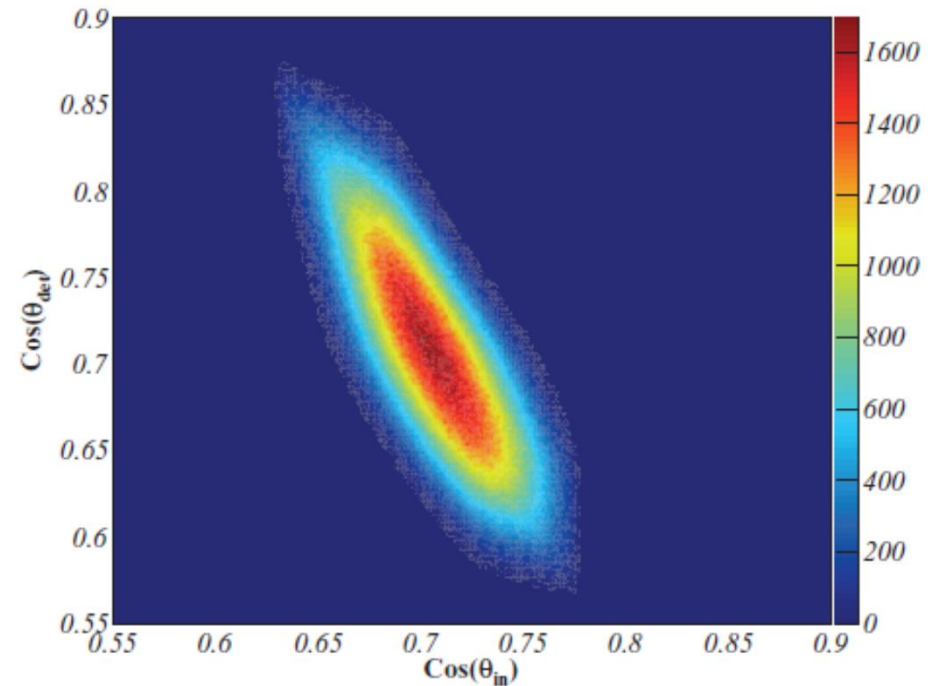
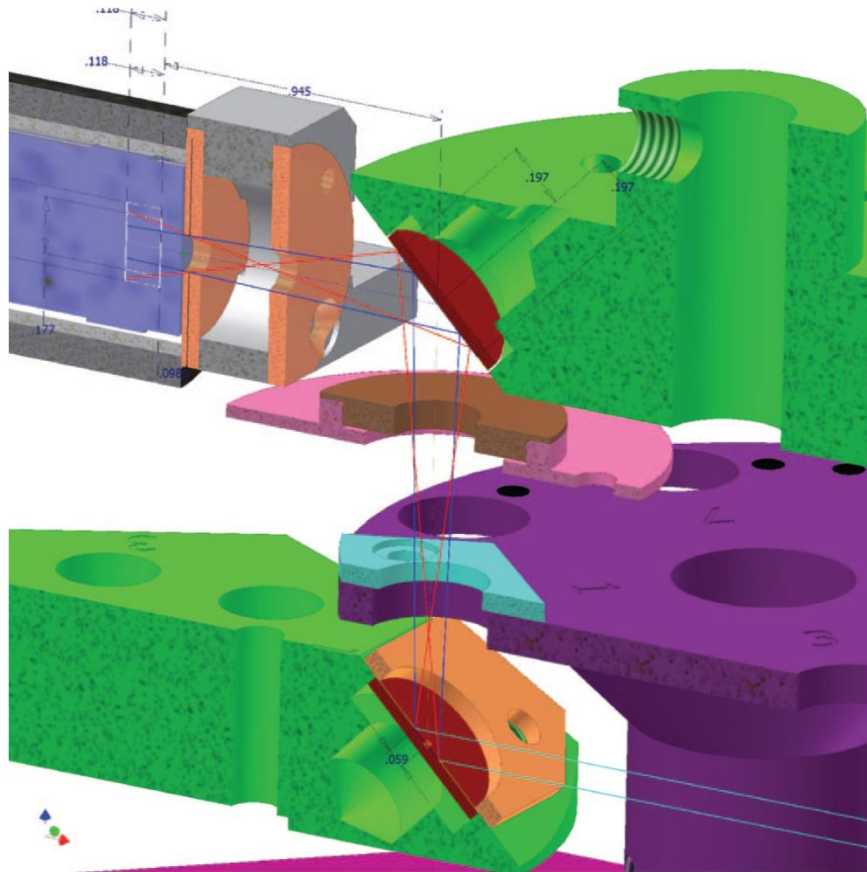
Secondary fluorescence enhancement

Z	WF (%)	I _{pr} (%)	I _{sec} (%)	I _{ter} (%)	I _{scat} (%)
Al	8.4	1	21.2	1.17	1.2
Si	26.7	1	18.1	0.64	1.23
Ca	9.3	1	13.8	-	1.64
Fe	9.8	1	-	-	2.44

$$\psi_1 = \psi_2 = 45^\circ$$

$$E_0 = 17.44 \text{ keV} \\ (\text{Mo} - K_a)$$

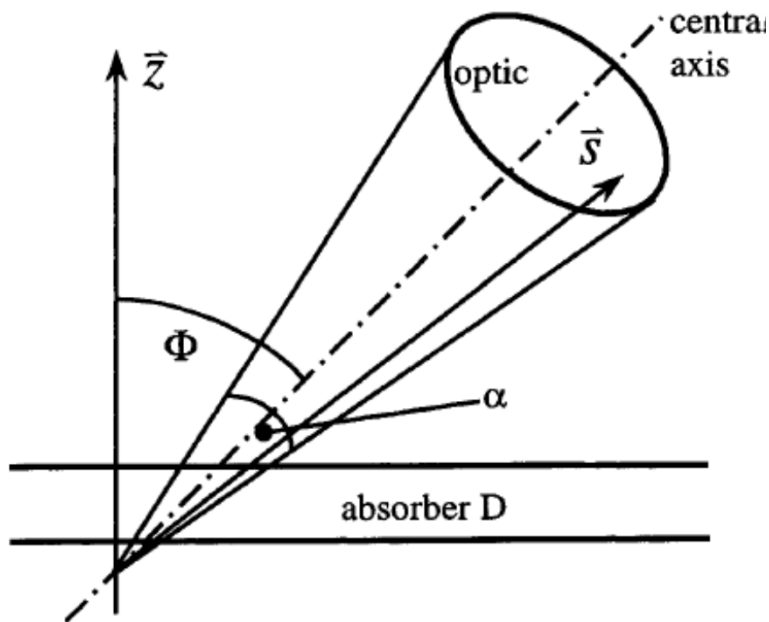
Geometrical considerations: Non-parallel x-ray beams



$$\vartheta_{in}=45.2^\circ \text{ and } \vartheta_{out}=44.7^\circ$$

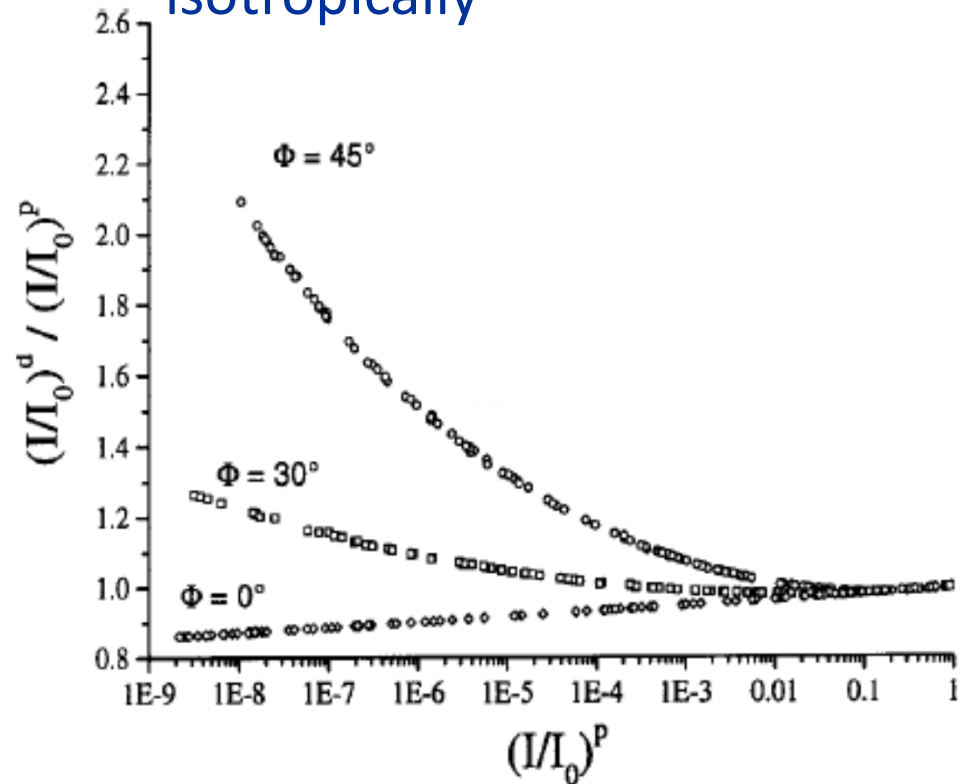
Sokaras et al., Review of Scientific Instruments 83, 123102 (2012);

Fluorescence intensities for non-parallel x-ray beams



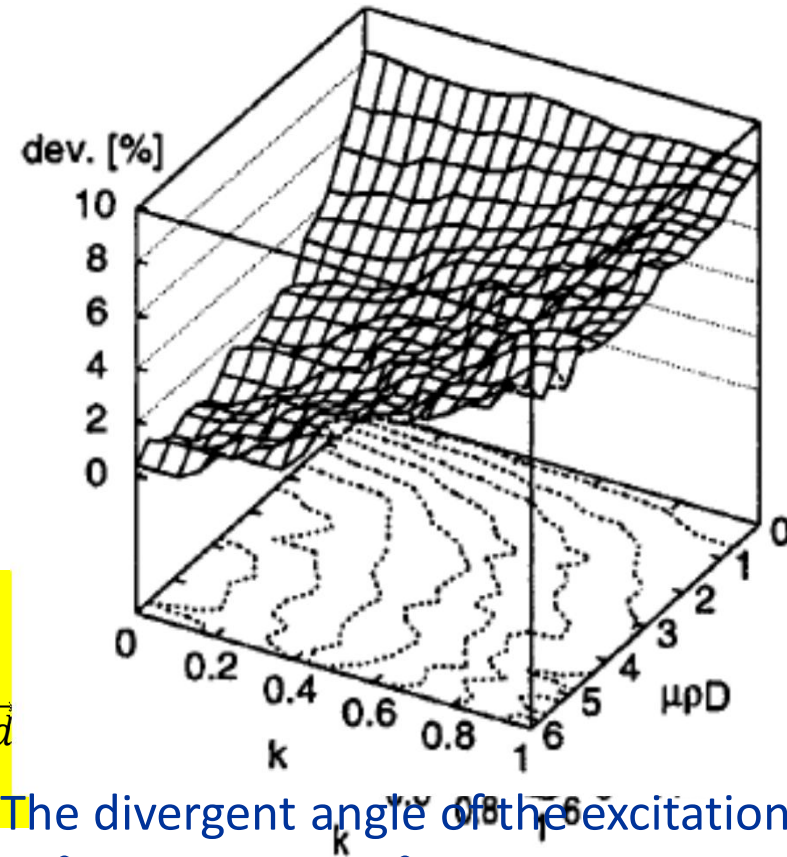
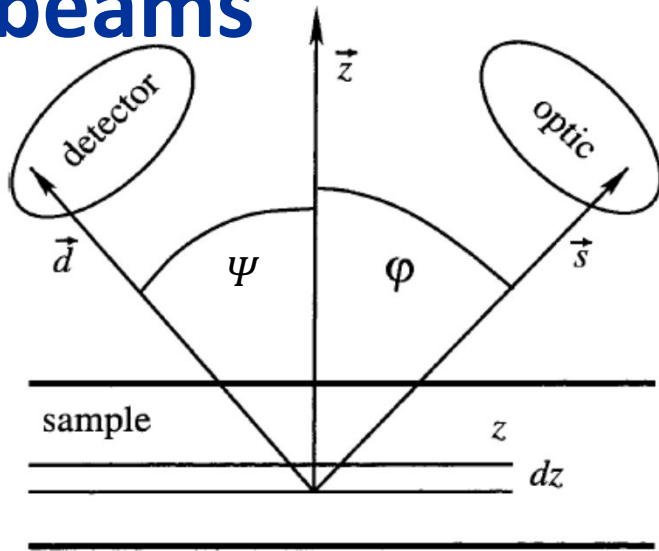
$$\left(\frac{I}{I_0}\right)^d = \int p(\vec{s}) \exp\left(\frac{-\mu\rho D}{s_z}\right) d\vec{s}$$

The divergent angle Φ is 20° and the trajectories are distributed isotropically



Malzer, Kanngiesser, X-Ray Spectrom. 2003; 32: 106–112

Fluorescence intensities for non-parallel x-ray beams



$$I_i^d = \frac{I_0 K_i c_i}{\mu} \int p(\vec{s}) p(\vec{d}) \frac{1 - \exp\left[-\mu \rho D \left(\frac{k}{d_z} + \frac{1-k}{s_x}\right)\right]}{k \frac{s_z}{d_z} + (1-k)} d\vec{s} d\vec{d}$$

$$\cos \theta = s_z \text{ and } \cos \Psi = d_z$$

$$\mu = \mu_0 + \mu_i$$

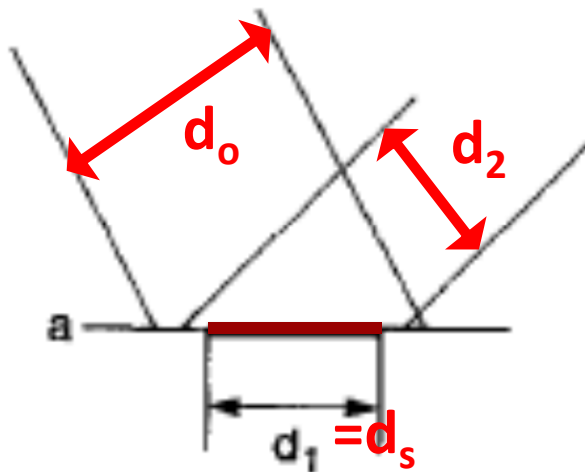
$$k = \mu_i / \mu$$

The divergent angle of the excitation is 60° and the optic lens with a divergent angle of 10° is positioned perpendicular towards the sample surface. Detector angle of 20° .

Geometrical considerations in XRF intensities

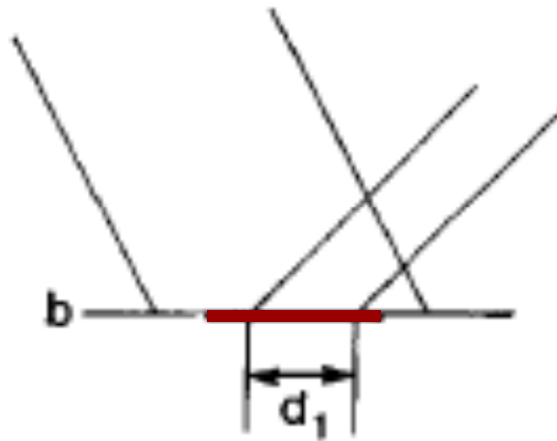
Incident flux I_0 is expressed in number of photons/s/cm²

$$G = \frac{\Delta\Omega}{4\pi} \times \frac{wd_s}{a^2} \sin \vartheta_1$$



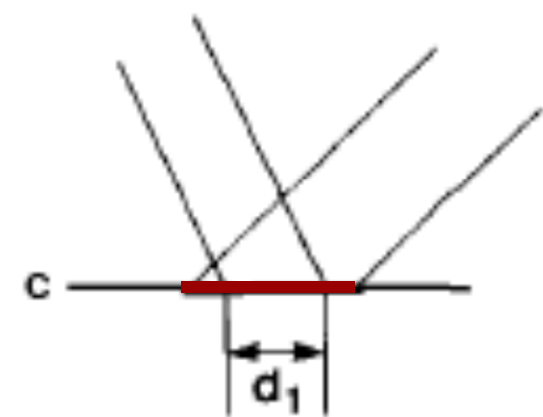
$$G \propto \sin \vartheta_1$$

$$G = \frac{\Delta\Omega}{4\pi} \times \frac{wd_2}{a^2} \times \frac{\sin \vartheta_1}{\sin \vartheta_2}$$



$$G \propto \frac{\sin \vartheta_1}{\sin \vartheta_2}$$

$$G = \frac{\Delta\Omega}{4\pi} \times \frac{wd_o}{a^2}$$

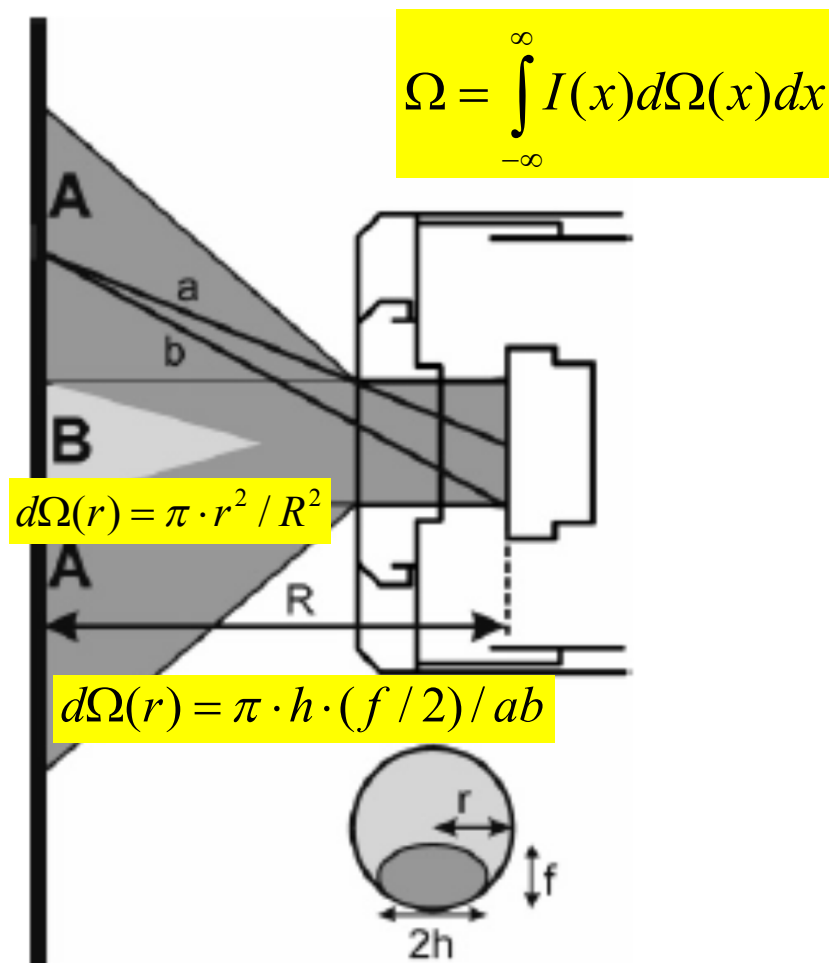


$$G = \text{const}$$

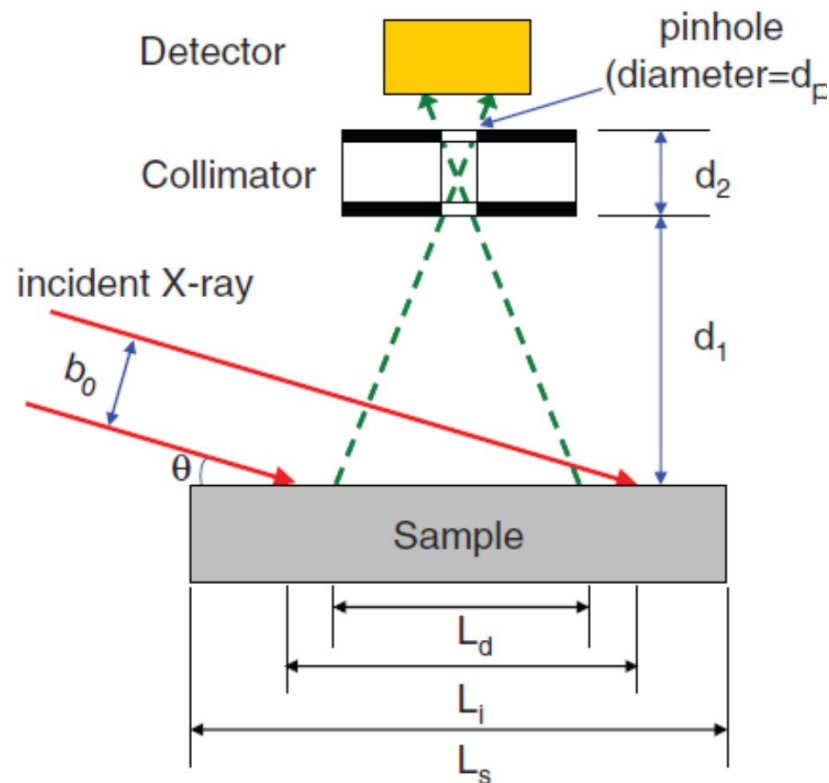
De Boer, XRS, 18, 119, 1989

Geometrical considerations in XRF intensities

Geometry under GI conditions



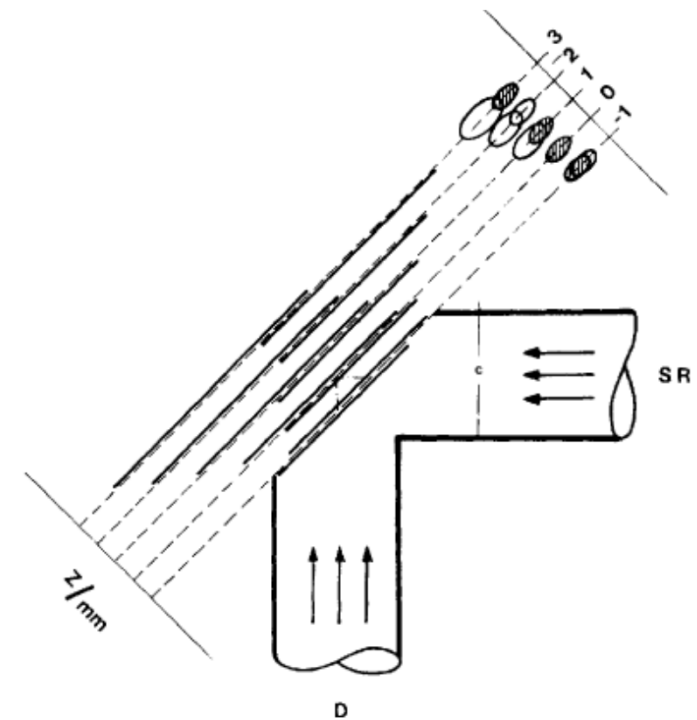
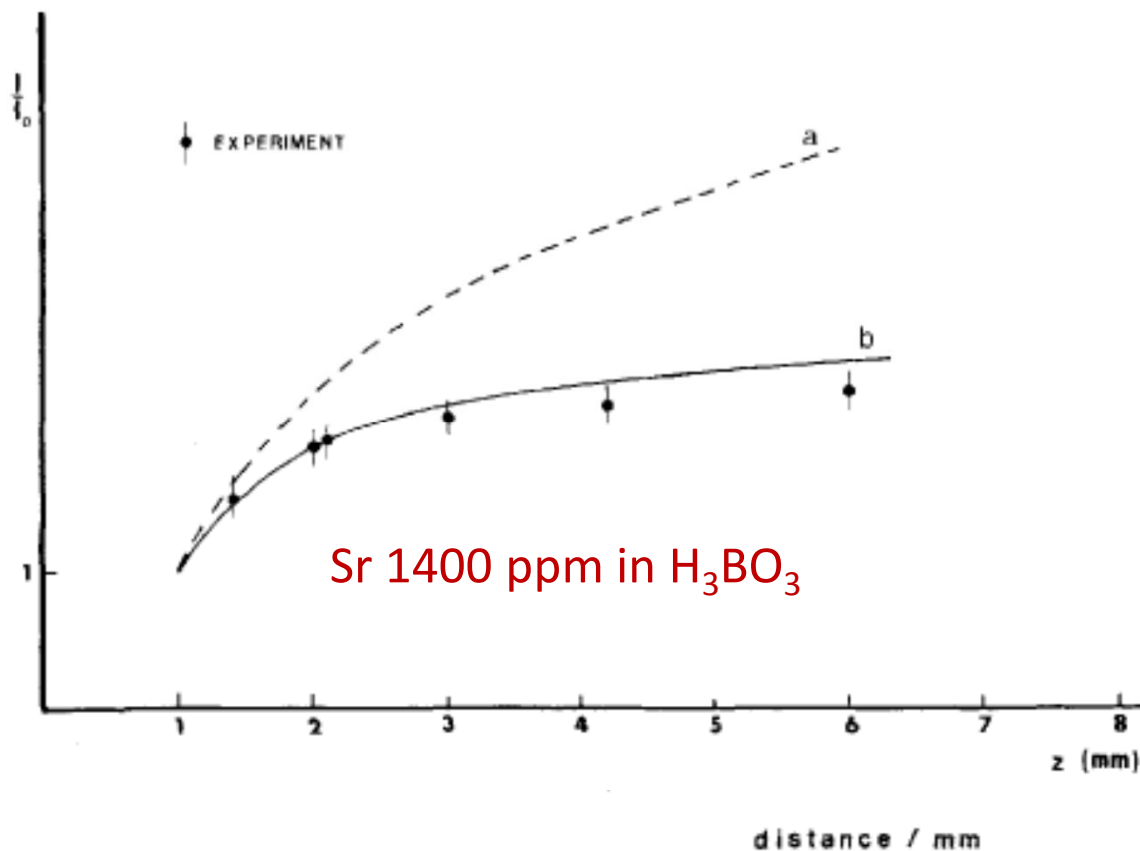
B. Beckhoff et al Anal. Chem. 2007



Weblin IJ, Rev. Sci. Instrum. 83, 053114 (2012); doi: 10.1063/1.4722495

Geometrical considerations in XRF intensities

Sample Volume effect in milli-beam size XRF set-ups

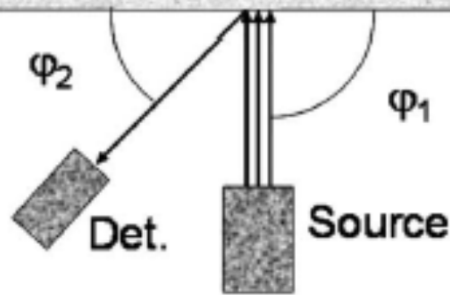


Orlic et al. XRS, 16, 125-130 (1987)

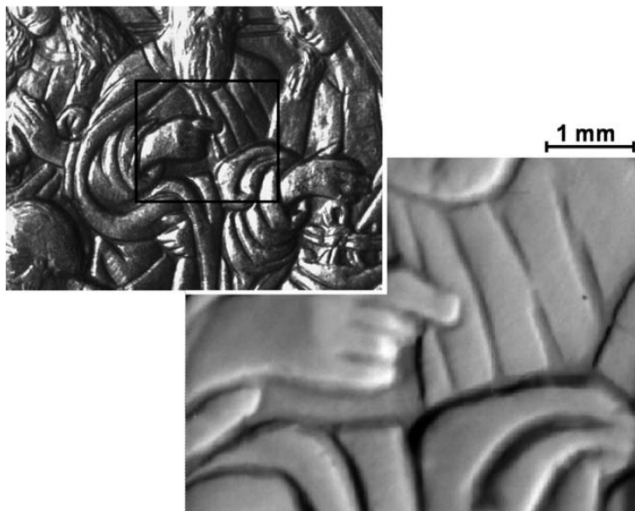
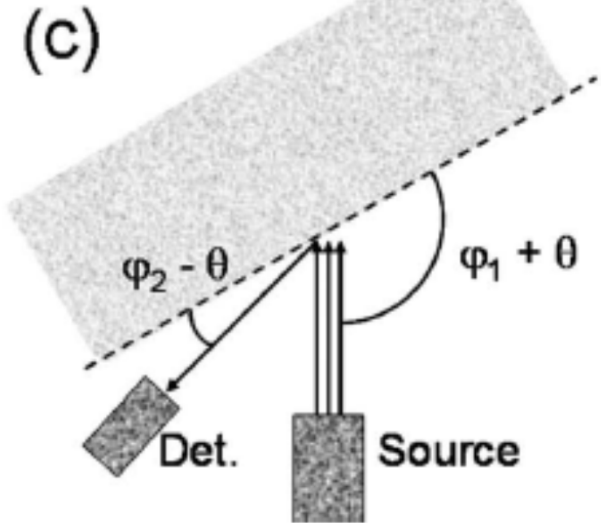
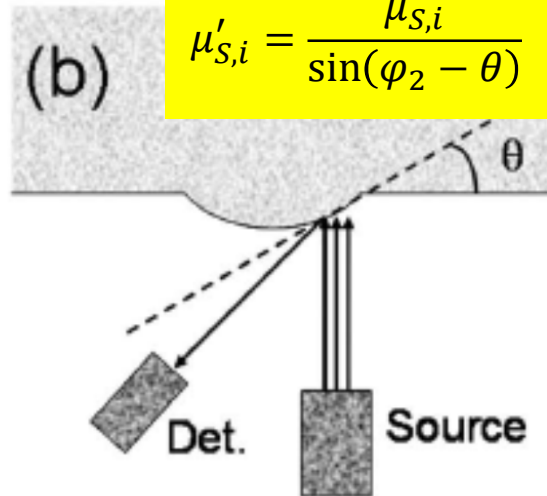
Effect of Surface Topography in XRF intensities

$$N_i = \frac{K_i C_i}{\sin(\varphi_1 + \theta)} \left(\sum_E \frac{\tau_{i,E}}{\mu'_{S,E} + \mu_{S,i}^N} I(E) \Delta E + \sum_j \sum_J C_j g_J \tau_{i,j} \times \sum_E \frac{\tau_{j,E} I(E) \Delta E}{\mu'_{S,E} + \mu_{S,i}^N} L_{i,J} \right)$$

(a) $\mu'_{S,E} = \frac{\mu_{S,E}}{\sin(\varphi_1 + \theta)}$



(b) $\mu'_{S,i} = \frac{\mu_{S,i}}{\sin(\varphi_2 - \theta)}$



T. Trojek, *J. Anal. At. Spectrom.*, 2011, 26, 1253

A.G. Karydas, *ICTP-IAEA School, Trieste*, 18th November 2014

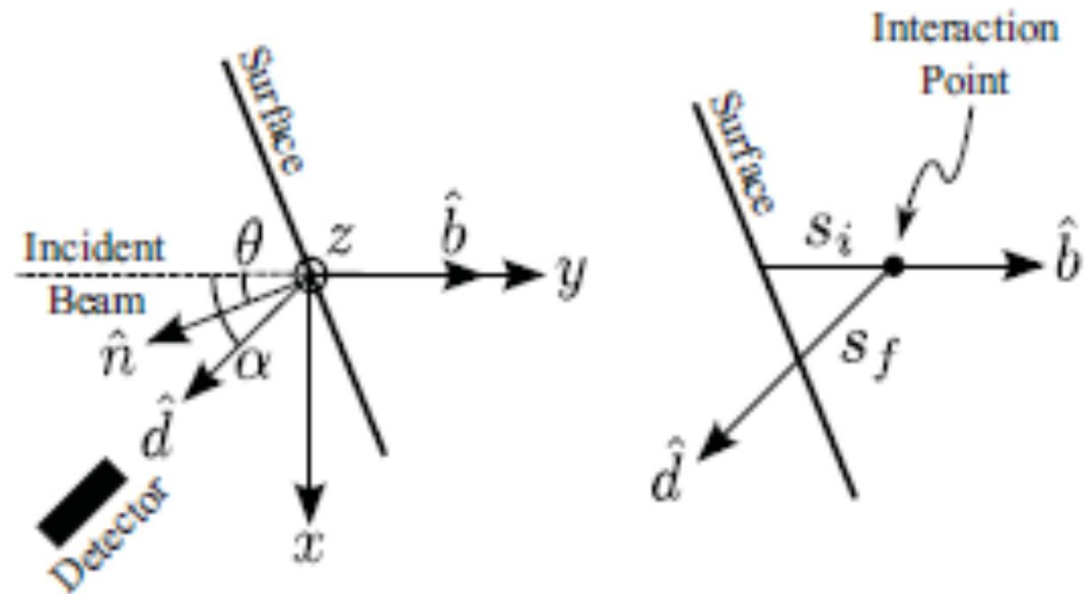
10-12-10

Effect of Surface Topography in XRF intensities

$$\hat{n} \cdot (s_i \hat{b} + s_f \hat{d}) = 0$$

$$s_f = -\frac{\hat{b} \cdot \hat{n}}{\hat{d} \cdot \hat{n}} s_i \equiv k \cdot s_i$$

$$k = (\cos a + \tan \theta \sin \alpha)^{-1}$$



$$I = \lambda \int_0^{\infty} \exp[-(\mu_i + k\mu_f)s_i] ds_i = \frac{\lambda}{\mu_i + k\mu_f}$$

$$I(\theta) \propto \frac{1}{1 + \left(\frac{\mu_f}{\mu_i}\right) (\cos a + \tan \theta \sin a)^{-1}}$$

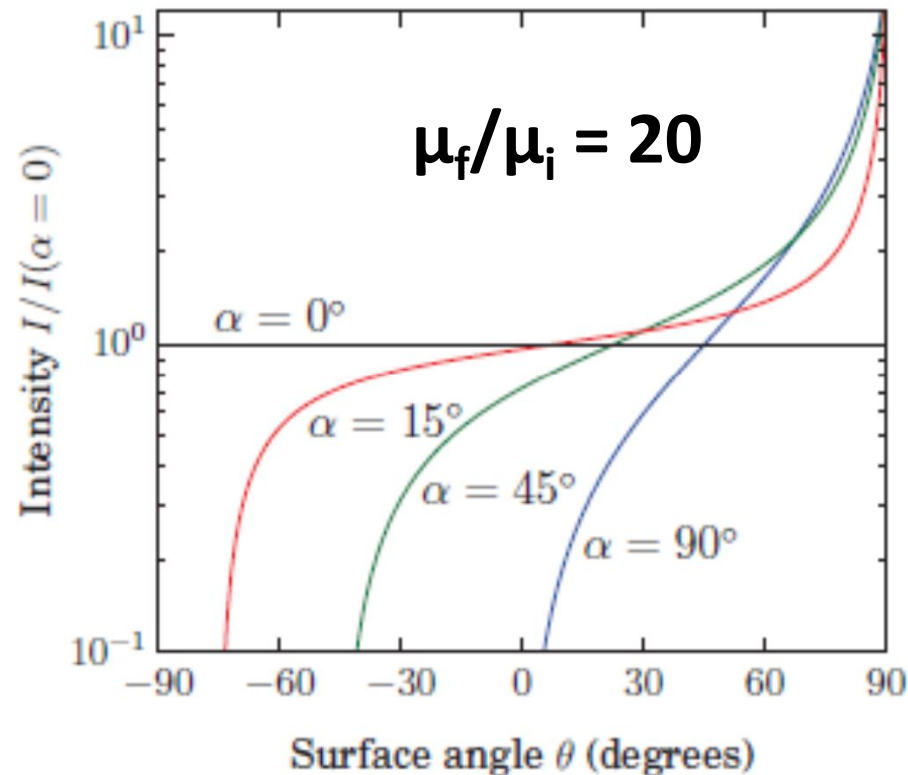
ϑ is the rotation of the surface normal around the z axis; $\vartheta = 0$ for a surface parallel to the xz plane

E. C. Geil and R. E. Thorne, *J. Synchrotron Rad.* (2014), 21, 1358-1363

Effect of Surface Topography in XRF intensities

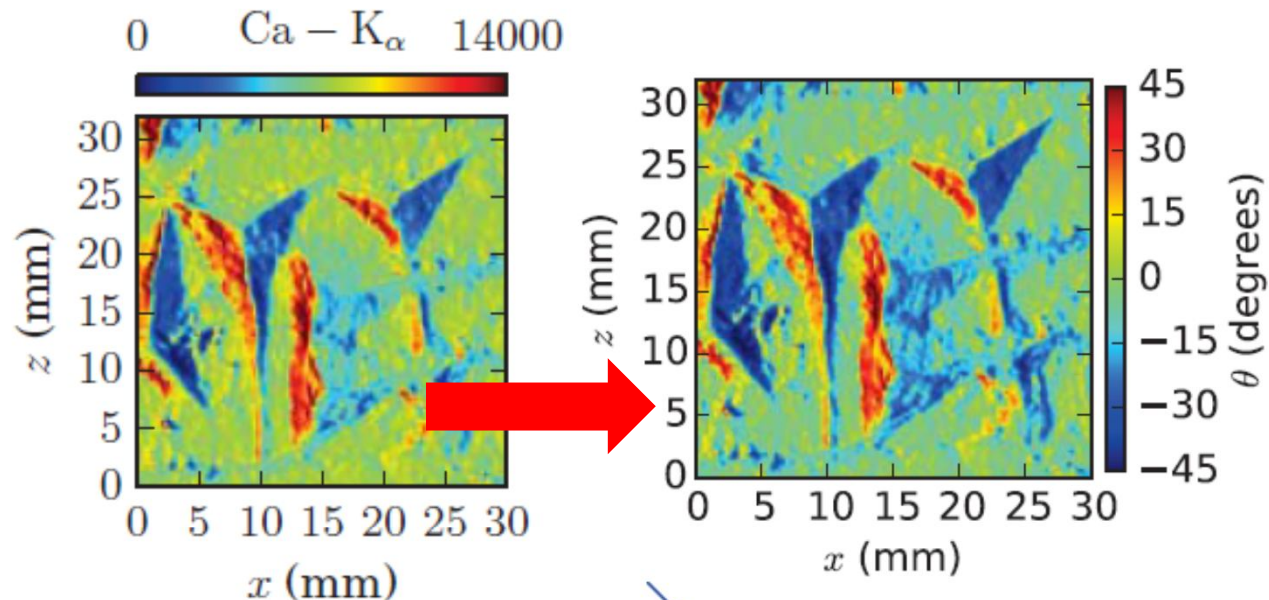
Hints:

The objects should be mounted so that their dominant surface curvature runs perpendicular to the detector–incident beam (x-y) plane



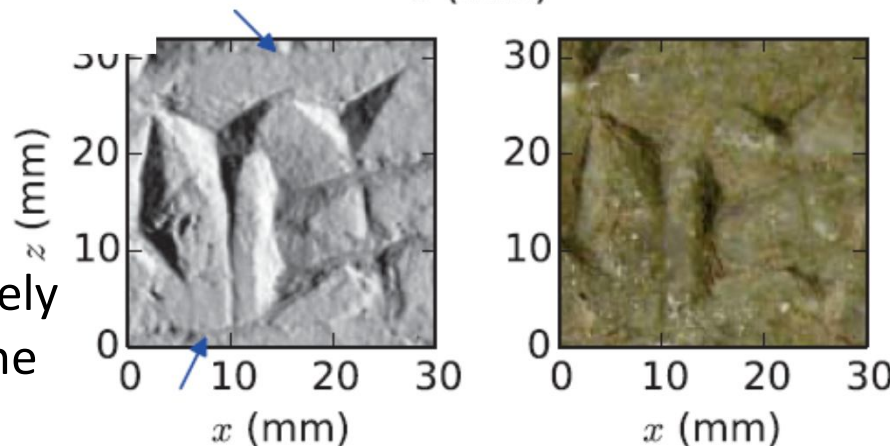
The angle effect vanishes as the detector position approaches the incident beam, and it is maximal when the detector is perpendicular to the beam. CaCO₃ matrix, with incident beam energy 16.5keV

Effect of Surface Topography in XRF intensities



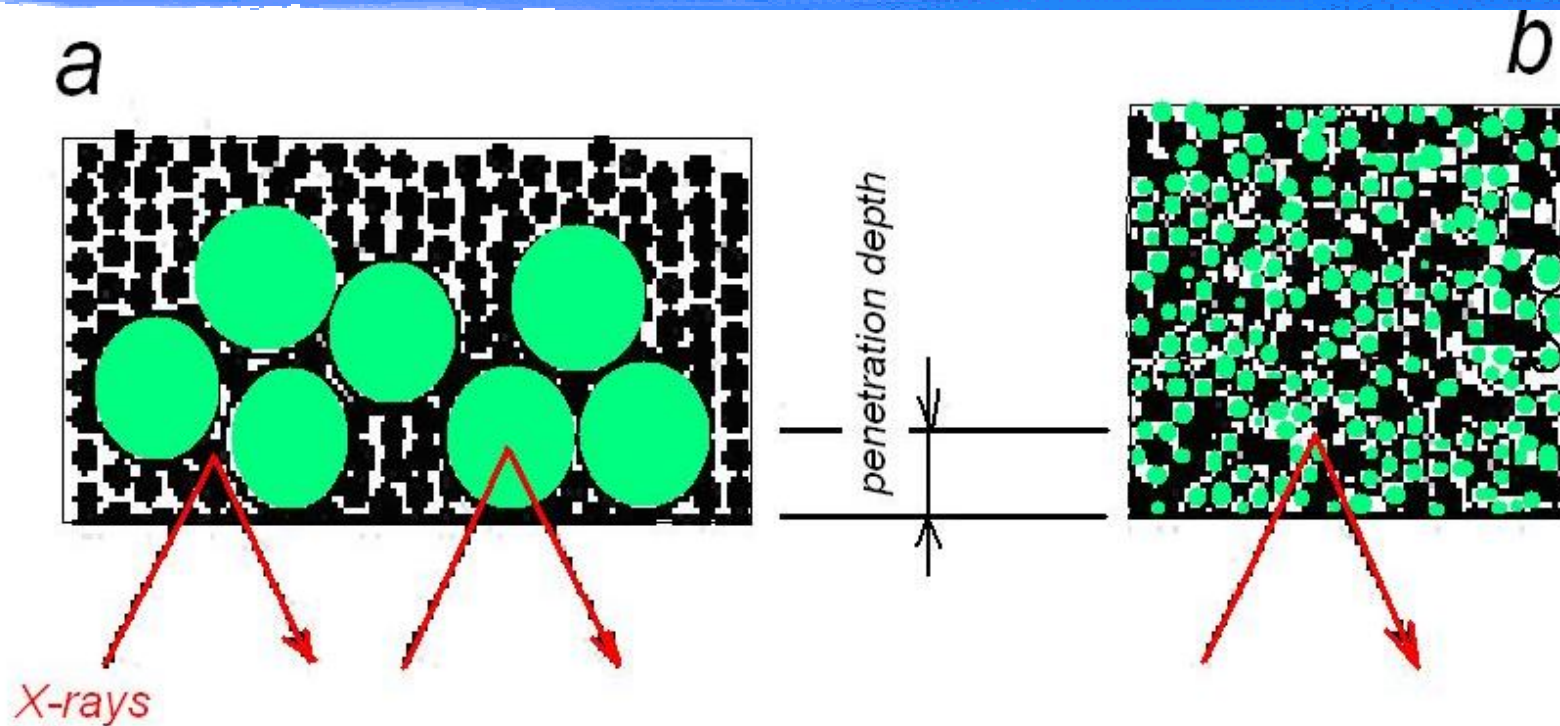
Map of surface angle θ computed from the Ca - K α fluorescence

Rendering of the scanned area and shaded as if obliquely illuminated from the right side by a light source.



Photograph of the scanned area, adjusted to enhance contrast and brightness.

Sample effects – Particle size



Example: Fe₂O₃

50% of 8 -12 keV from 30μm – 60μm

90% of 8 -12 keV from 100μm – 200μm

Information originates only from the first two layers

Particle size correction models

□ Berry et al (Adv. X-ray Anal. 12, 612 1969)

o Dependence of fluorescence intensity on:

• $\bar{d} = 2/3$ diameter of sphere

• $\eta =$ packing ratio, $m = \frac{c_{nf}}{c_f}$ $D \approx 10nm$

$$P_{ja} = \frac{1 - \exp[(\mu_f + \mu'_f) \cdot \rho_f \cdot \bar{d}]}{1 - \exp[(\mu_f + \mu'_f) \cdot \rho_f \cdot D]} \cdot \frac{\{1 - \eta + \eta \cdot \exp(-\mu_f \cdot \rho_f \cdot D) + \eta \cdot m \cdot \exp(-\mu_{nf} \cdot \rho_{nf} \cdot D)\}}{\{1 - \eta + \eta \cdot \exp(-\mu_f \cdot \rho_f \cdot \bar{d}) + \eta \cdot m \cdot \exp(-\mu_{nf} \cdot \rho_{nf} \cdot \bar{d})\}}$$

$$\mu_f = \sum_f c_f \frac{\mu_f(E_0)}{\sin \psi_1} \quad \mu_{nf} = \sum_{nf} c_{nf} \frac{\mu_{nf}(E_0)}{\sin \psi_1}$$

$$\mu'_f = \sum_f c_f \frac{\mu_f(E_j)}{\sin \psi_2} \quad \mu'_{nf} = \sum_{nf} c_{nf} \frac{\mu_{nf}(E_j)}{\sin \psi_2}$$

Overview - Conclusions

- The quantitative XRF analysis is currently supported by a well-defined mathematical formalism based on the so-called fundamental parameters approach
- The majority of second/third order phenomena that affect the analyte fluorescence intensity are described by analytical formulas

Obstacles:

- ✓ Enhancement due to electrons ionization requires verification and currently is not taken into account routinely
- ✓ Accuracy of fundamental parameters (soft energy region) and for L, M characteristic X-rays

Perspectives

- ❑ Monte Carlo methods it is the most comprehensive tool to account for all high-order phenomena and assess their contribution in fluorescence intensities
- ❑ FP re-evaluation by means of metrological SR experiments

Acknowledgements

- ✓ Charalambos Zarkadas, PANalytical B.V. , The Netherlands
- ✓ Dimosthenis Sokaras, Stanford Synchrotron Radiation Lightsource, USA
- ✓ Vasiliki Kantarelou, INPP, NCSR “Demokritos”, Greece